

# ***High-Temperature Nano-Derived Micro-H<sub>2</sub> and -H<sub>2</sub>S Sensors***

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# Objectives

- Develop micro-scale, chemical sensors composed of nano-derived, metal-oxide materials which display stable performance within high-temperature environments ( $>500^{\circ}\text{C}$ ).
- Short term– Develop high-temperature  $\text{H}_2$  and  $\text{H}_2\text{S}$  sensor using low cost, easily reproducible methods with 3D porous nanomaterials.
- Long term – Develop high-temperature micro-sensor arrays to detect gases such as  $\text{NO}_x$ ,  $\text{SO}_x$ ,  $\text{H}_2\text{S}$ ,  $\text{H}_2$ , HCs.
- Collaboration with NexTech Materials, Ltd. (Lewis Center, OH).



# Proposed Work Plan

## **Task 2.0 Synthesis and Characterization of Nano-Composite Electrodes.**

Doped-tin oxide, ceria, zirconate (perovskite and pyrochlore), and molybdate/tungstate nanomaterials will be synthesized using hydrothermal and/or glycine-nitrate processes and characterized.

## **Task 3.0 Lost-Mold Microcasting of the Selective Electrode Structure.**

Develop microcasting methods for patterning microscale, chemically selective pads on alumina wafers.

**Task 4.0 Fabrication of Micro-Sensors and Arrays.** Fabricate functional hydrogen micro-sensors and micro-sensor arrays. In addition, stable IDEs for high-temperature applications must be developed.

## **Task 5.0 Micro-Sensor and Sensor Array Testing.**

Micro-sensors will be first characterized for baseline resistance using external furnace heat at temperatures ranging from 600°C to 1000°C. Key tests include:

- *Sensitivity and selectivity*
- *Humidity sensitivity (0-10% H<sub>2</sub>O)*
- *O<sub>2</sub> requirements (0.1-20%)*
- *CO cross-sensitivity (ppm-% CO)*
- *Temperature sensitivity (500-1000°C)*



# Proposed Work Schedule

Schedule of tasks and milestones												
Task/Milestone	Quarter after Project Initiation											
	1	2	3	4	5	6	7	8	9	10	11	12
<b>Task 1. Project Management and Planning (Q1-Q12)</b>												
<b>Subtask 1.1:</b> Kick-Off Meeting and Sensor Design at WVU.	■											
→ MS: Sensor and Array Established		▲										
<b>Subtask 1.2:</b> Project Meetings and Reporting	■											
→ DL: Quarterly Reports	●	●	●	●	●	●	●	●	●	●	●	●
→ DL: Annual Progress Reports				●				●				
→ DL: Final Technical Report												●
<b>Task 2. Synthesis and Characterization of Nano-Composite Electrodes. (Q1-Q7)</b>												
<b>Subtask 2.1:</b> Synthesis of Zirconate Electrode Compositions	■											
→ MS: Process for synthesizing $ABO_3$ and $A_2B_2O_7$ nano-powder established				▲								
<b>Subtask 2.2:</b> Composite Selective Electrodes	■											
→ DL: NexTech nano-catalyst delivered to WVU for stability testing			●									
<b>Subtask 2.3:</b> Electrode Characterization				■								
→ MS: Stability of $H_2$ and $H_2S$ nano-composites electrodes defined to 1200 °C						▲						
<b>Task 3. Lost-Mold Microcasting of the Selective Electrode Structure. (Q5-Q11)</b>												



Task/Milestone	Quarter after Project Initiation											
	1	2	3	4	5	6	7	8	9	10	11	12
<b>Task 3. Lost-Mold Microcasting of the Selective Electrode Structure. (Q5-Q11)</b>												
<b>Subtask 3.1: Micro-Mold Fabrication</b>												
→ MS: Microcasting process defined						▲						
→ DL: Micro-molds delivered to NexTech for commercial microcasting demonstration					●	●	●	●				
<b>Subtask 3.2: Lost-Mold Microcasting and Sintering of Micro-Selective Electrode</b>												
<b>Subtask 3.3: Selective Electrode (SE) Characterization.</b>												
<b>Task 4. Fabrication of Micro-Sensors and Arrays (Q6-Q12)</b>												
<b>Subtask 4.1: Pt Interconnect and Counter-Electrode (CE) Deposition</b>												
<b>Subtask 4.2: Selective Electrode (SE) Deposition/Sintering</b>												
→ MS: Micro-sensor fabricated												
<b>Subtask 4.3: H<sub>2</sub>-H<sub>2</sub>S Micro-Sensor Array Fabrication</b>												
→ MS: Micro-sensor array fabricated												
<b>Task 5. Micro-Sensor and Sensor Array Testing (Q8-Q12)</b>												
<b>Subtask 5.1: Testing of H<sub>2</sub> micro-sensors</b>												
→ MS: Micro-sensor specification targets achieved												▲
→ DL: Delivery of sensors to NexTech for testing							●	●	●	●	●	
<b>Subtask 5.2: Testing of H<sub>2</sub>S micro-sensors and H<sub>2</sub>-H<sub>2</sub>S array</b>												
→ MS: Micro-sensor array specification targets achieved												▲



# *Proposed Milestones*

- Sensor and Sensor Array design established – Q2
- Process for synthesizing nanomaterials established – Q4
- Stability of H<sub>2</sub> and H<sub>2</sub>S nano-composites electrodes defined – Q8
- Micro-casting process defined – Q6
- Micro-sensors fabricated – Q8
- Micro-sensor array fabricated – Q9
- Micro-sensor specification targets achieved – Q11
- Micro-sensor array specification targets achieved – Q12

**Closure of testing labs in January at WVU due to aged ventilation.  
Remodeling expected to be completed in August.**



# *Proposed Deliverables*

- 1) **Quarterly and annual progress reports to DOE**
- 2) **Subtask 2.2-** industrial partner delivers nanomaterials to WVU for stability testing **(Q3)**
- 3) **Subtask 3.1-** Micro-molds delivered to industrial partner for commercial microcasting demonstration **(Q5-8)**
- 4) **Subtask 5.1-** Delivery of micro-sensors to industrial partner for testing **(*delivery start of each quarter Q7-Q11*)**
- 5) **Subtask 5.2-** Delivery of arrays to industrial partner after testing- ***delayed due to testing.***



# *Presentations of this Work*

1. “High temperature nano-derived hydrogen sensors,” Christina Wildfire, Engin Ciftyurek, Katarzyna Sabolsky, Edward M. Sabolsky, [European Ceramics Society \(ECerS\) XII](#) conference in Stockholm, Sweden, June 19-23 2011, Nanomaterials Symposium; **INVITED PRESENTATION**
2. “Performance and Stability of High-Temperature Nano-Derived Hydrogen Sensors,” Edward M. Sabolsky, Christina Wildfire, Engin Ciftyurek, Katarzyna Sabolsky, 220th [Electrochemical Society Meeting](#), Boston, MA, Oct. 9-14, 2012; **PRESENTATION**
3. “High-Temperature Nanomaterials for Electrochemical Micro-Sensors,” Edward M. Sabolsky, Christina Wildfire, Engin Ciftyurek, [Energy Materials and Applications \(EMA\) 2012](#) Conference in Orlando, FL, January 18-20, 2012, S1: New Frontiers in Electronic Ceramic Structures, Advanced Electronic Material Devices and Circuit Integration; **PRESENTATION**
4. “Nano-Derived, Micro-Chemical Sensors for High-Temperature Applications,” Edward M. Sabolsky, Christina Wildfire, Engin Ciftyurek, Katarzyna Sabolsky, 221st [Electrochemical Society Meeting](#) in Seattle, WA, May 6-10, 2012; **INVITED PRESENTATION**
5. “High-Temperature Nano-Derived Chemical Micro-Sensors,” Edward M. Sabolsky, Christina Wildfire, Engin Ciftyurek, Katarzyna Sabolsky, [10th International Symposium on Ceramic Materials and Components for Energy and Environmental Applications \(CMCEE\) 2012](#) in Dresden, Germany, May 20-23, 2012; **PRESENTATION**



# *Presentations of this Work*

- 6) “Nano-Derived, Micro-Chemical Sensors for High-Temperature Applications,” E. M. Sabolsky, C. Wildfire, E. Ciftyurek, K. Sabolsky, 221st [Electrochemical Society Meeting](#) in Seattle, WA, May 6-10, 2012; **INVITED PRESENTATION.**
- 7) “High-Temperature Compatible Electrodes with Various Microstructural Architectures,” E. Çiftyürek, K. Sabolsky, and E.M. Sabolsky, 221st [Electrochemical Society Meeting](#) in Seattle, WA, May 6-10, 2012; **PRESENTATION.**
- 8) “Degradation of Platinum Thin Films Electrodes for High-Temperature MEMS Applications”, E. Çiftyürek, K. Sabolsky and E. M. Sabolsky, [WV Academia Science 2012](#) Charleston, West Virginia, USA. **PRESENTATION.**
- 9) “High-Temperature Nano-Derived Sensors for Online Monitoring of SO<sub>2</sub> Emissions”, E. Çiftyürek, C. Wildfire, and E. M. Sabolsky, [Materials Science & Technology 2012](#), Pittsburgh, Pennsylvania, USA. **PRESENTATION.**
- 10) “High-Temperature Nano-derived Sensor Development for Detection of H<sub>2</sub>S and SO<sub>2</sub> Emissions.” E. Çiftyürek, K. Sabolsky, and E. M. Sabolsky, [Materials Science & Technology 2013](#), Quebec, Canada. **TO BE PRESENTED.**



# Publications of this Work

- 1) E. Çiftyürek, K. Sabolsky, and E. M. Sabolsky, “Platinum Thin Film Electrodes for High-Temperature Chemical Sensor Applications.”, [Published](#) in Sensors and Actuators B: Chemical, ISSN 0925-4005, 10.1016/j.snb.2013.02.058.
- 2) E.M. Sabolsky, C. Wildfire, E. Çiftyürek, and K. Sabolsky, “Nano-Derived, Micro-Chemical Sensors for High-Temperature Applications”, [Published](#) in ECS Transactions, 45 (3) 495-506 (2012).
- 3) C. Y. Wildfire, E. Çiftyürek, K. Sabolsky, and E. M. Sabolsky, “Investigation of Doped-Gadolinium Zirconate Nanomaterials for High-Temperature Hydrogen Sensor Application”, [Accepted](#) to Sensors and Actuators B: Chemical, March 2013.
- 4) C. Y. Wildfire, E. Çiftyürek, K. Sabolsky, and E. M. Sabolsky, “Development and Testing of High Temperature Hydrogen Micro-Sensors.”, [Submitted](#) to Sensor Letters, in June 2013.
- 5) E. Çiftyürek, K. Sabolsky, and E. M. Sabolsky “Functionally Gradient Zr-Pt Composite Thin Films for Stable High-Temperature Electrodes”, [To be submitted](#) to Journal of Microelectromechanical systems, in June 2013.
- 6) C. Wildfire, E. Çiftyürek, K. Sabolsky, and E. M. Sabolsky, “High Temperature Semiconducting Hydrogen Sensors Based on Lanthanum Stannate Materials”, [To be submitted](#) to Sensors and Actuators B: Chemical, in August 2013.

3 more publications currently being prepared for H<sub>2</sub>S and SO<sub>2</sub> sensing.



# Background



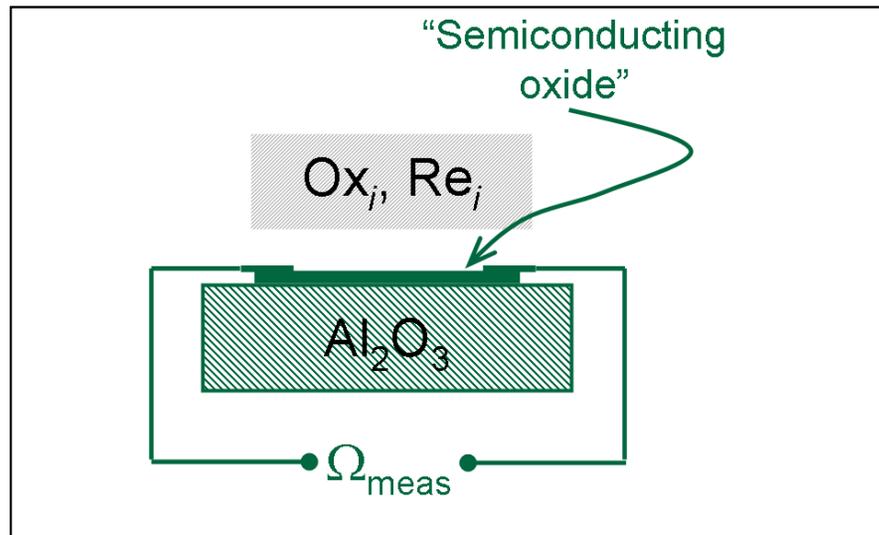
# **Background– Sensor Requirements**

## **Regardless of Sensor Type:**

- a) Chemically stable
- b) Reversible
- c) Fast
- d) Highly sensitive
- e) Durable
- f) Simple operation
- g) Small size (portability, reduction in cost, rapid response)



# Background-High-Temp Solid State Sensors



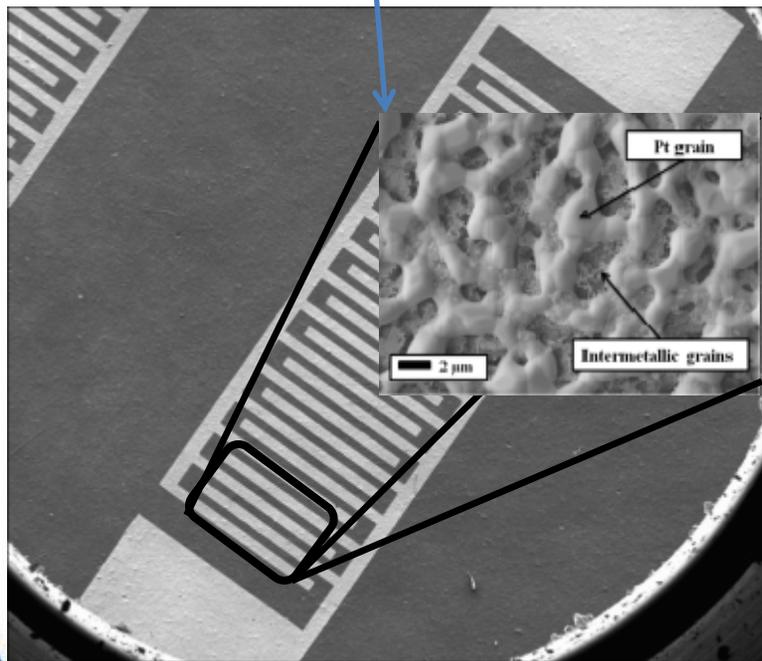
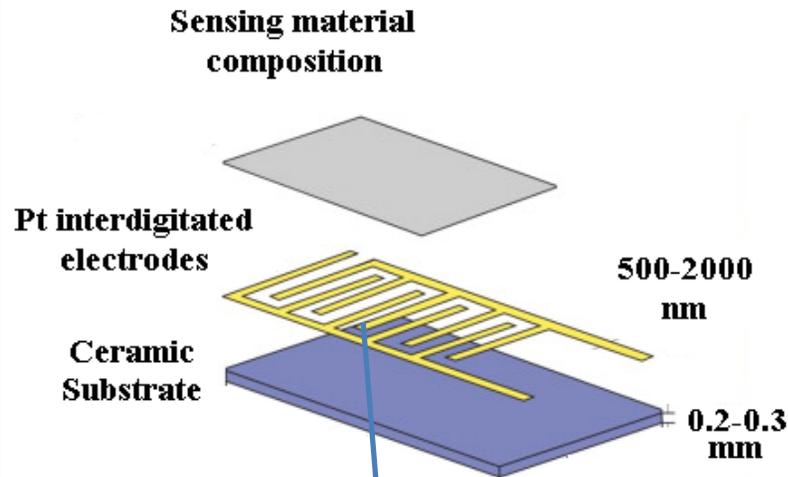
\*T. Armstrong presentation, 20th Annual Fossil Energy Conference (2006).

## Chemiresistive- (Resistive-type)

- Absorption / interaction with surface alters resistivity.
- Typical operating  $T \leq \sim 600^\circ\text{C}$  (band gap and stability limited).
- Simple design allows for micro-chemical sensor arrays.
- Selectivity problem due to sensitivity mechanism.



# Background- Chemiresistive Sensors

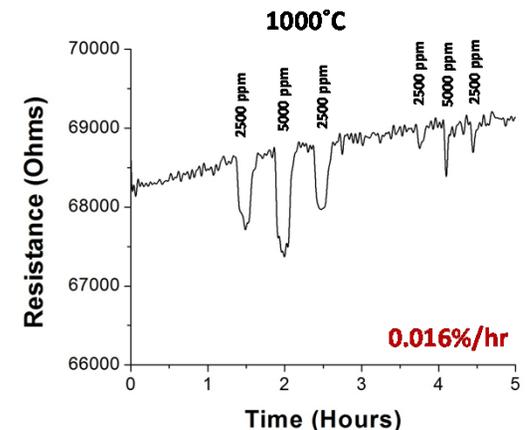
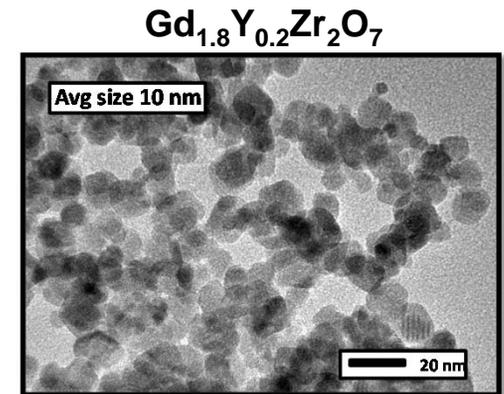


1. Adsorption of chemical species on metal-oxide surface causes redox reaction (change in current carriers).
2. Affects depletion area thickness resulting in a change in the resistance.
3. Metal-oxide semiconductor's (MOS) shape, size, composition, and surface characteristics controls the selectivity and sensitivity.
4. Nanomaterials provide ultra-high surface area and will enhance interaction with chemical species.



## Presented in Previous Reviews (2010-2012)

- 1) Hydrothermal processes for synthesis of ionic and mixed-conducting zirconate, stannate, and titanate pyrochlores (3-10 nm).
- 2) Resistor-type, macro-sensors of composite nanomaterials sense 500-4000 ppm H<sub>2</sub> (in air) at 600-1000°C.
- 3) Nano-zirconate and SnO<sub>2</sub>/zirconate nano-composites displayed enhanced stability.
  - From 0.792%/hr to 0.016%/hr  
(0.014 sensitivity for 500 ppm at 1000°C)
- 4) Initiated work on Pt-based micro-IDEs that are stable to 1200°C.
- 5) Initiated development of micro-casting and Dip Pen Nanolithography (DPN) processes for fabricating micro-sensor arrays.



## Challenges Current Work Addresses:

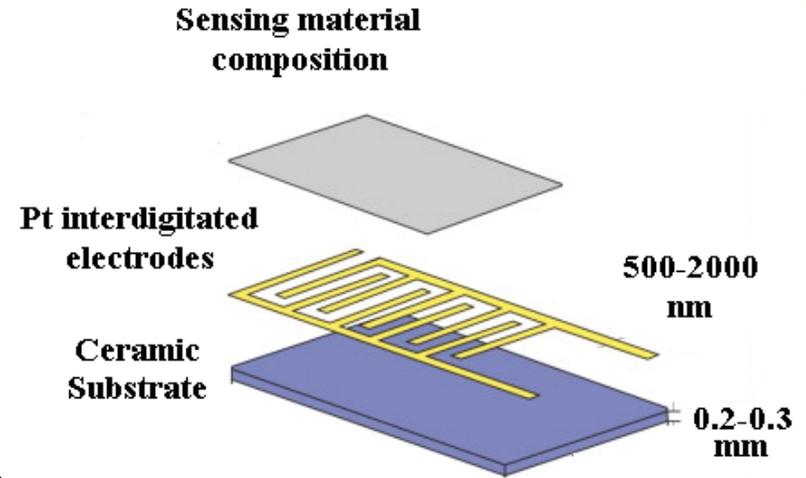
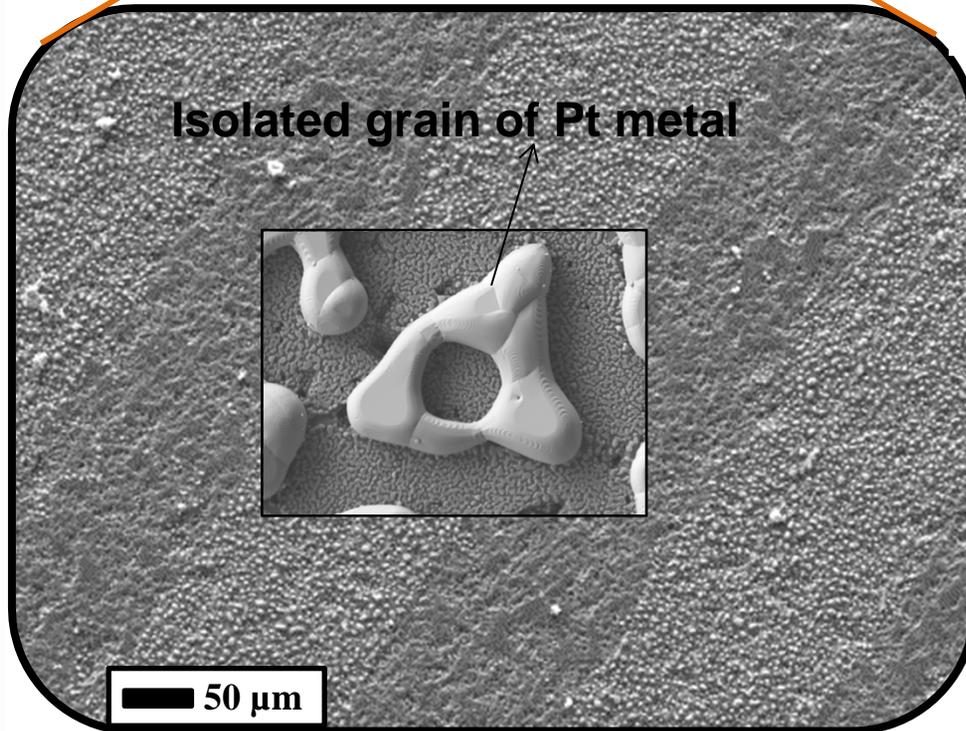
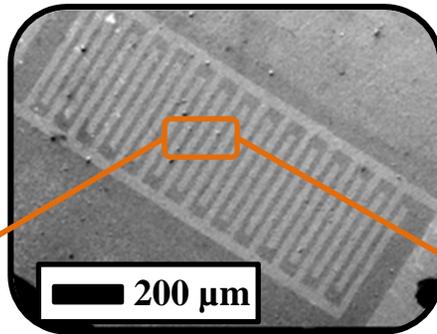
- 1) *High-temperature stable micro-electrodes.*
  - a. *Develop stable, DC sputtered micro-electrodes for specific sensing mechanism.*
  - b. *Method for depositing and patterning potential complex microstructures and refractory metals.*
  
- 2) *High-temperature, stable, nanomaterials for sensing ( $H_2S$ ,  $SO_2$ ).*
  - a. *Selective to species of interest.*
  - b. *React with other gas species in environment.*
  - c. *Morphological stability at high temperature due to sintering and coarsening mechanisms (Driving Force  $\approx 1/D^n$ ).*
  
- 3) *Method to micro-pattern particulate nanomaterials.*



***High-Temperature Stable Electrodes  
(Inter-Digitized Electrodes, IDEs)***



# IDE Limitations



Current sensor technology is limited to operate at low temperature due to

- Sensing material composition
- Processing
- **Incapable electrodes**

**Breaks Apart !!!**



# Strategy to Stabilize IDEs

•Using intermediate layer  
i.e. adhesion layer.



**Surface  
tension**

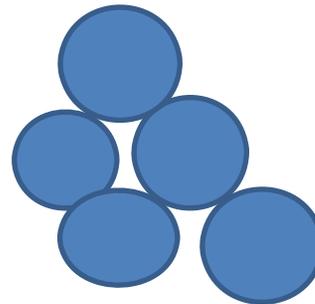
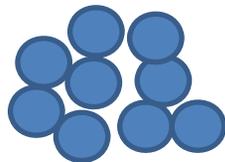


**Combat**

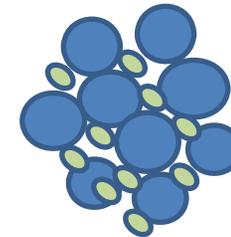
•Using second phase  
precipitation.



**Coarsening**



**Coarsening/Sintering**



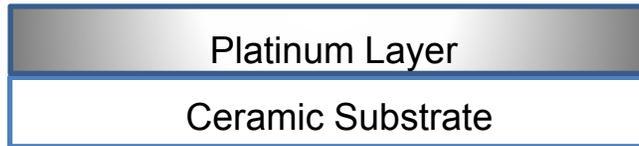
**Grain Boundary  
Pinning Hinders  
Coarsening.**

- : Pt grain
- : Second phase grain

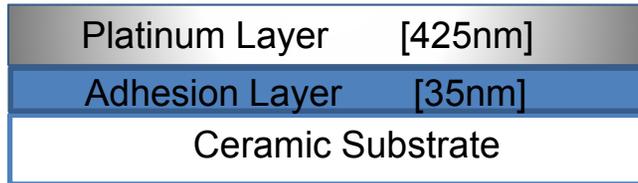


# Strategy to Stabilize IDEs

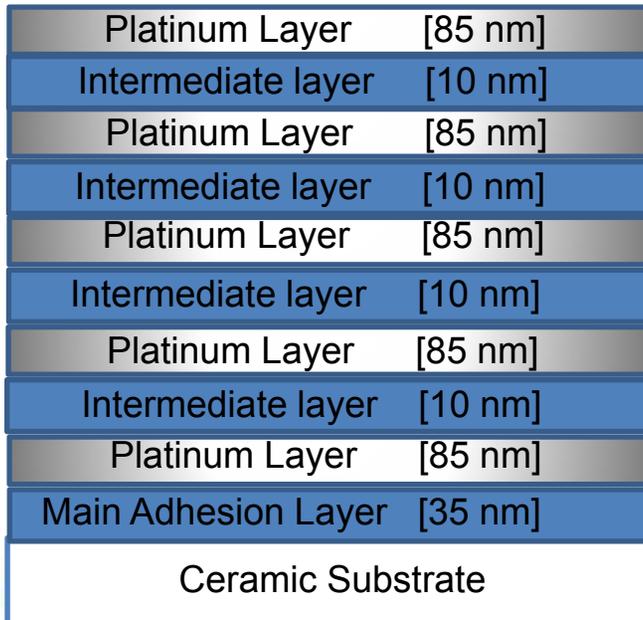
Schematic Representations



Pure Pt



BILAYER COATING ARCHITECTURES	
Titanium	Ti+Pt
Tantalum	Ta+Pt
Zirconium	Zr+Pt
Hafnium	Hf+Pt

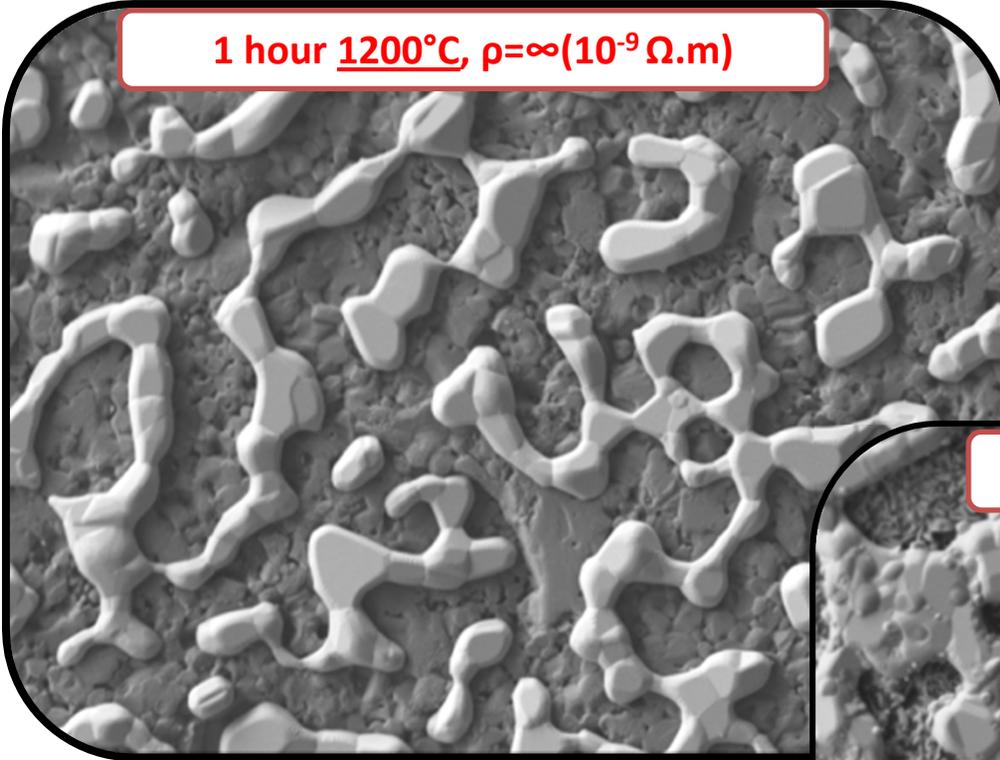


MULTILAYER COATING ARCHITECTURES	
Zirconium	L-Zr+Pt
Hafnium	Hf+L-Zr+Pt



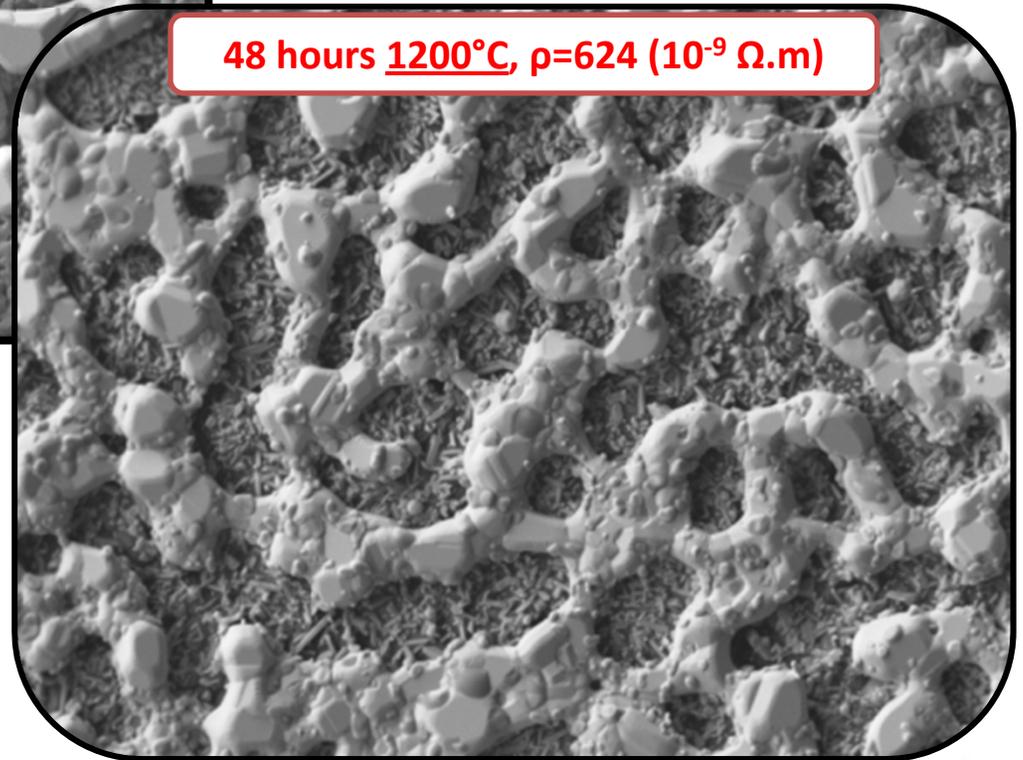
## Summary: IDE Stabilization

1 hour 1200°C,  $\rho = \infty (10^{-9} \Omega.m)$



Ti or Ta adhesion  
layer + Pt layer

48 hours 1200°C,  $\rho = 624 (10^{-9} \Omega.m)$



Hf adhesion layer + Zr+Pt  
composite



# Summary: High-Temp IDE Patterning

• Simple **Lift-off** process for electrode manufacturing.

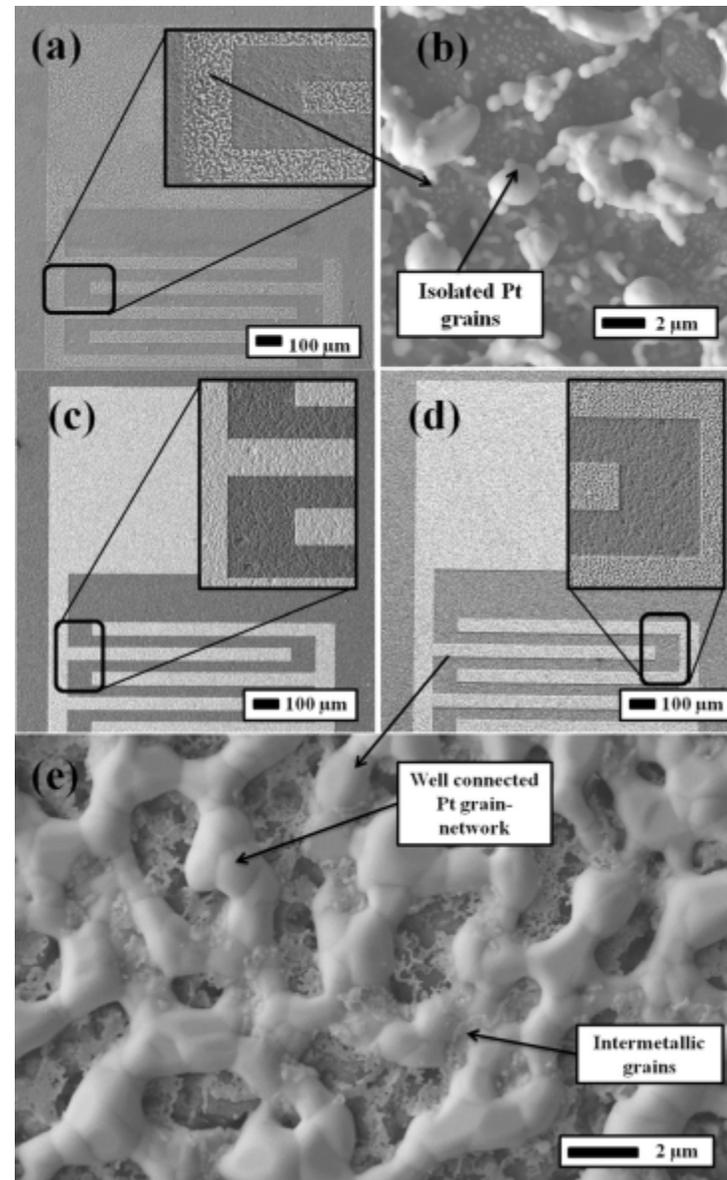
(a) Zr + Pt bilayer electrode after annealing at 1200°C 15 h

(b) Close look After annealing at 1200°C for 15 h.

(c) As-deposited Hf/L-Zr + Pt multilayer electrode, inset shows the edges closely.

(d) High magnification SEM image shows the edge of 15 h 1200°C annealed electrode.

(e) High magnification SEM image shows the edge of Hf/L-Zr + Pt electrode after annealing at 1200°C for 15 h.



***Nano-Derived Sensing Materials  
And Testing***



# Background-Sensing Materials for Sulfur Compounds

Chemiresistive and Potentiometric, and very limited number SAW devices.

## Chemiresistive Type

**WO<sub>3</sub>** thick/thin film with different deposition methods

**WO<sub>3</sub>** with different noble metal loadings (Pt, Pd, Au, Ag)

TiO<sub>2</sub>, V<sub>2</sub>O<sub>5</sub> modified **WO<sub>3</sub>** and loaded with Au

**NASICON-V<sub>2</sub>O<sub>5</sub>/WO<sub>3</sub>/TiO<sub>2</sub>** and/or decorated with noble metals

**Cr<sub>2-x</sub>Ti<sub>x</sub>O<sub>3</sub>** (insufficient sensing at temperature range 100-350°C).

**Ferrites**, 0-10% even at temperatures between 100-400°C

## Potentiometric Type

**Na<sub>2</sub>SO<sub>4</sub>-BaSO<sub>4</sub>-Ag<sub>2</sub>SO<sub>4</sub>**

**YSZ-LiSO-MgO**

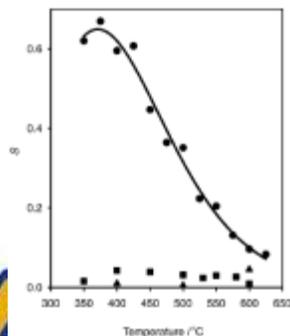
**Li<sub>2</sub>SO<sub>4</sub>-BaSO<sub>4</sub>**

**(Al<sub>0.2</sub>Zr<sub>0.8</sub>)<sub>10/19</sub>Nb(PO<sub>4</sub>)<sub>3</sub>**

**Li<sub>2</sub>SO<sub>4</sub>-doped La<sub>2</sub>O<sub>2</sub>SO<sub>4</sub>**

**NASICON, β-alumina and YSZ**

**K<sub>2</sub>SO<sub>4</sub> Li<sub>2</sub>SO<sub>4</sub>-Ag<sub>2</sub>SO<sub>4</sub>**



**V-doped TiO<sub>2</sub>,  
1000 ppm SO<sub>2</sub>**

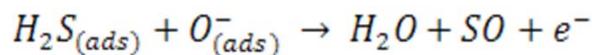
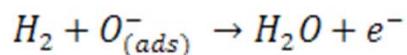
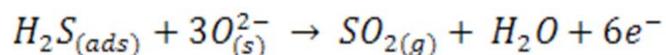
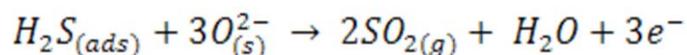
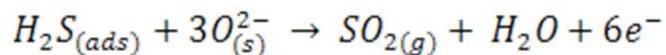
Morris *et al.*, J.Mat. Che, 2001

- Commercial product able to work up to 50°C.
- Not able to work at temperatures higher than 500°C
- Simple structure, design and packaging, cheap.

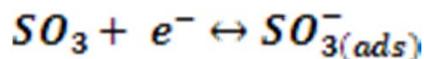
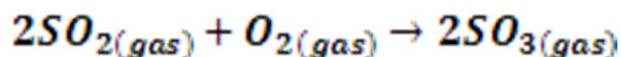
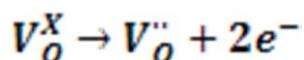
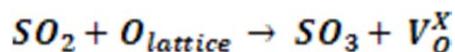
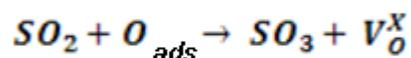
# Background-Sensing Materials for Sulfur Compounds

General proposed reactions that occur during sensor operation.

## H<sub>2</sub>S



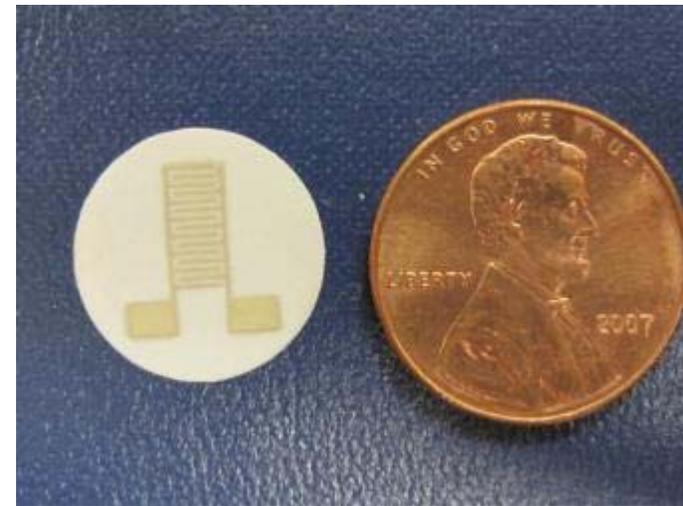
## SO<sub>2</sub>



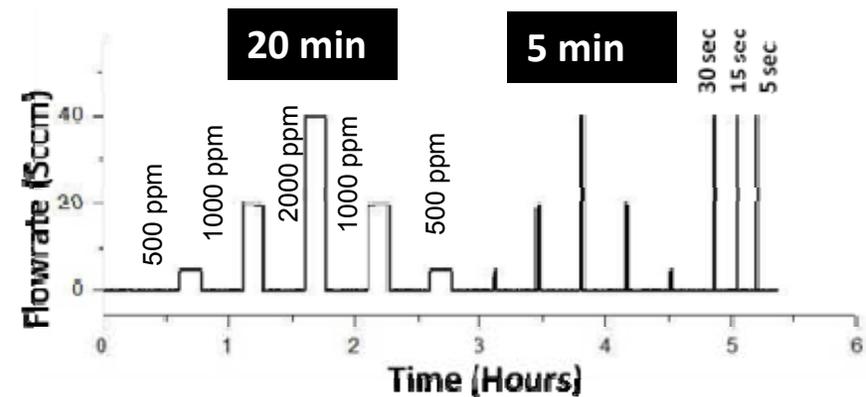
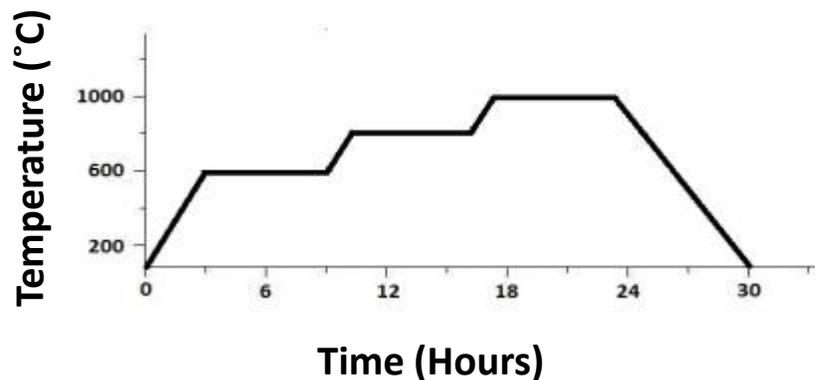
# Testing Protocol

## Macro Platform Properties and Testing Procedure

- Polished alumina substrates.
- Pt-IDEs screen-printed and annealed at 1200°C.
- Sensing material printed onto electrodes and sintered at 1200°C (~100 μm thick).
- Three different temperature regimes (600, 800, 1000°C)
- Three different O<sub>2</sub> partial pressures (1, 5 and 20 %)
- After each exposure to CO, H<sub>2</sub>, SO<sub>2</sub> and H<sub>2</sub>S , 30 minutes N<sub>2</sub> atmosphere relaxation.



Screen-printed Macro Electrode  
(250 μm finger spacing)



$$\text{Sensitivity} = S = \frac{R_{\text{gas}} - R_{\text{base}}}{R_{\text{base}}}$$



## Evaluation Sensing Materials for SO<sub>2</sub>

- Tungstates and molybdates, wide band gap semiconductors (4-5 eV) and double-prevooskites

- Microstructural, chemical and morphological stability at high temperatures.

- WO<sub>3</sub>

- WO<sub>3</sub> nano

- MoO<sub>3</sub>

- MoO<sub>3</sub> nano

- MgMoO<sub>4</sub>

- NiMoO<sub>4</sub>

- NiWO<sub>4</sub>

- Sr<sub>2</sub>MgWO<sub>6</sub> (SMW)

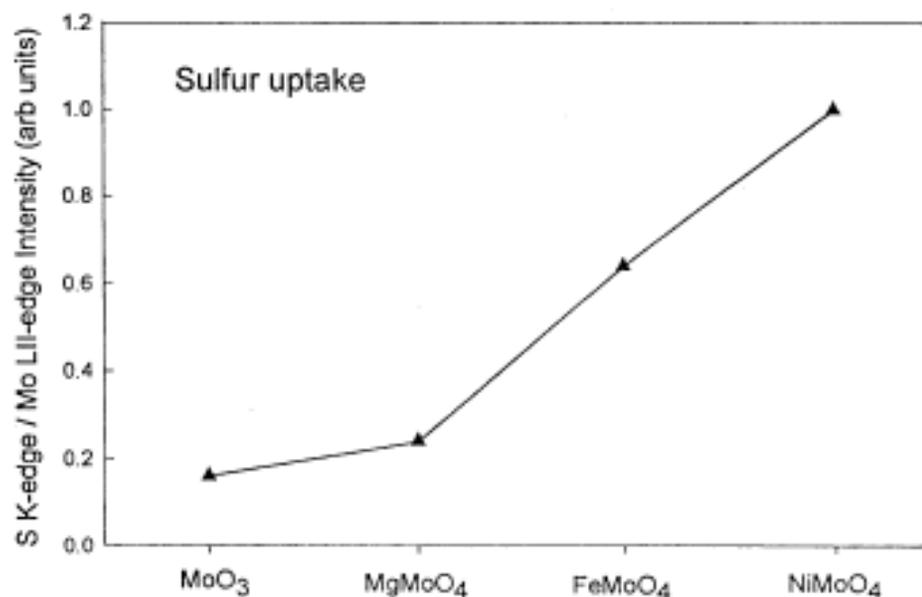
- Sr<sub>2</sub>MgMoO<sub>6</sub> (SMM)

- SrMoO<sub>4</sub>

- SrMoO<sub>4</sub> nano

- SrWO<sub>4</sub>

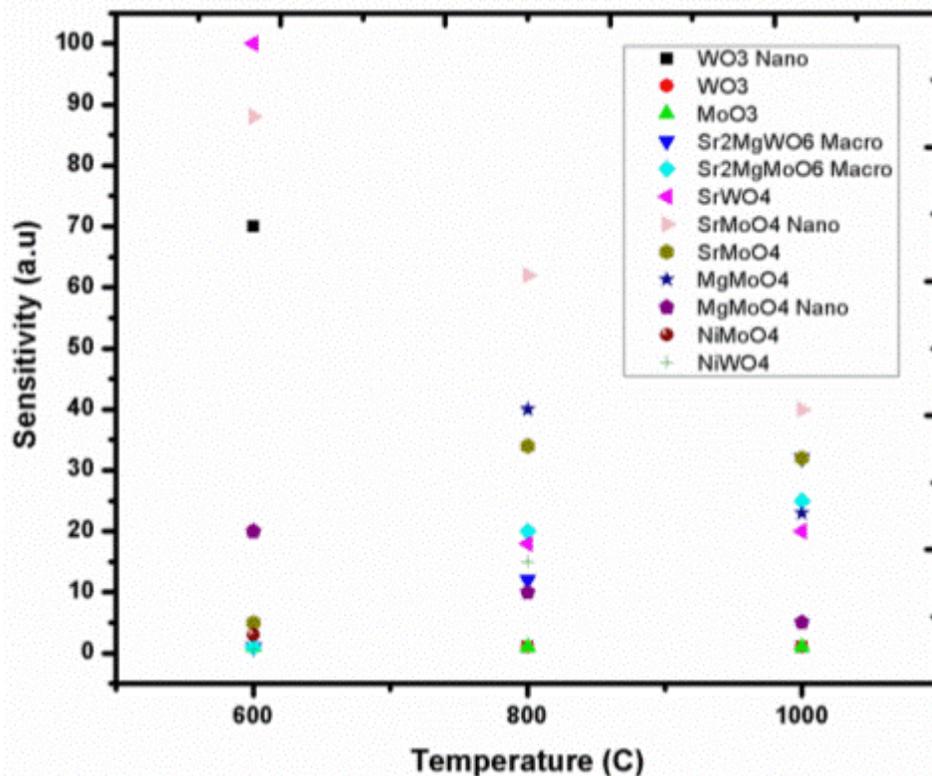
- Candidate compositions were tested in macro scale due to their sulfur uptake capabilities and suitable ones synthesized in nano-scale for further sensor tests.



J. A. Rodriguez, Catalysis Today, 2003

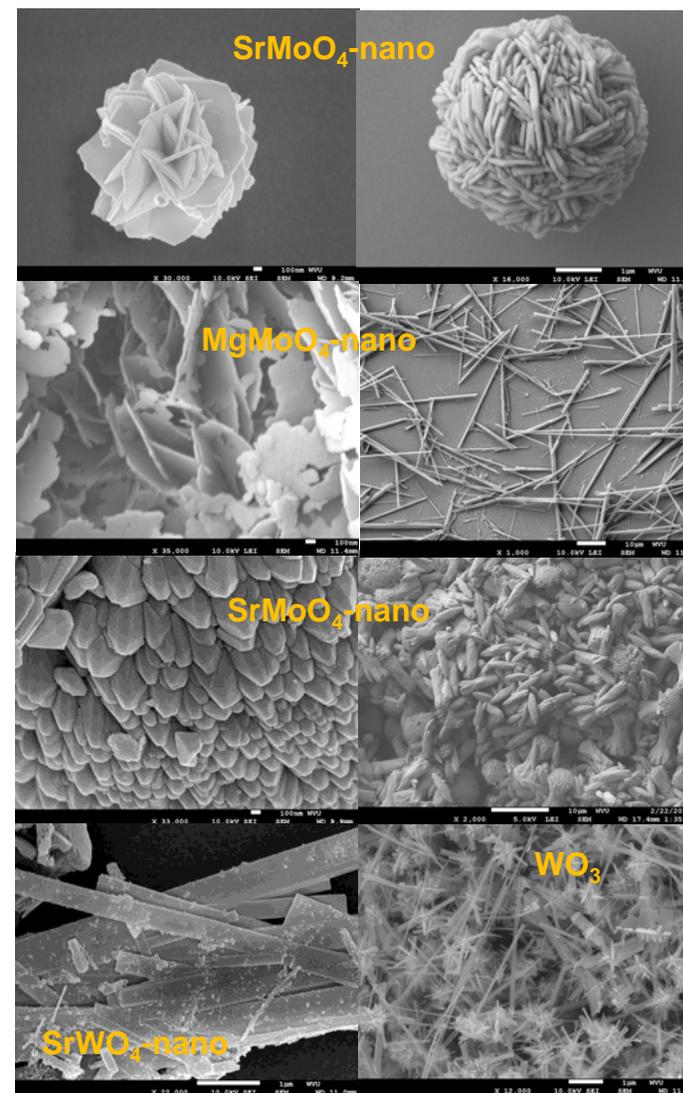


# Evaluation Sensing Materials for $SO_2$



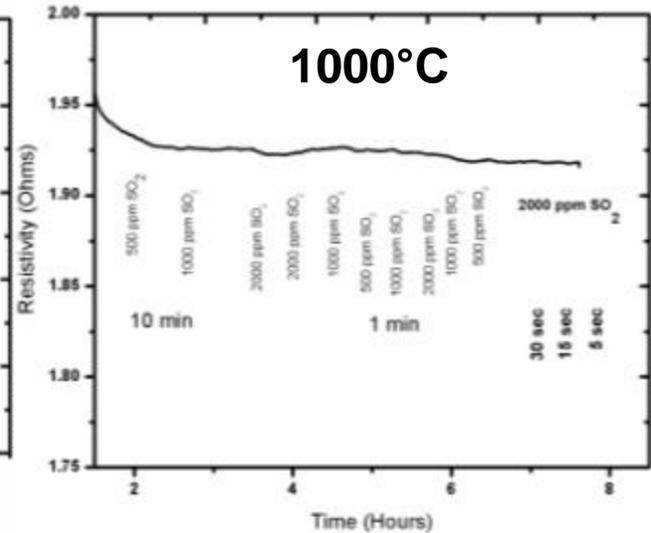
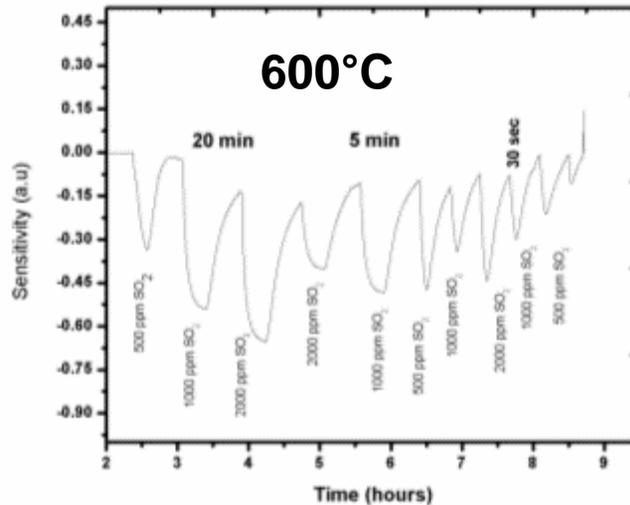
- 2000 ppm  $SO_2$  at 600, 800 and 1000 °C with 1%  $O_2$ .

• A few of the compositions will be discussed in details

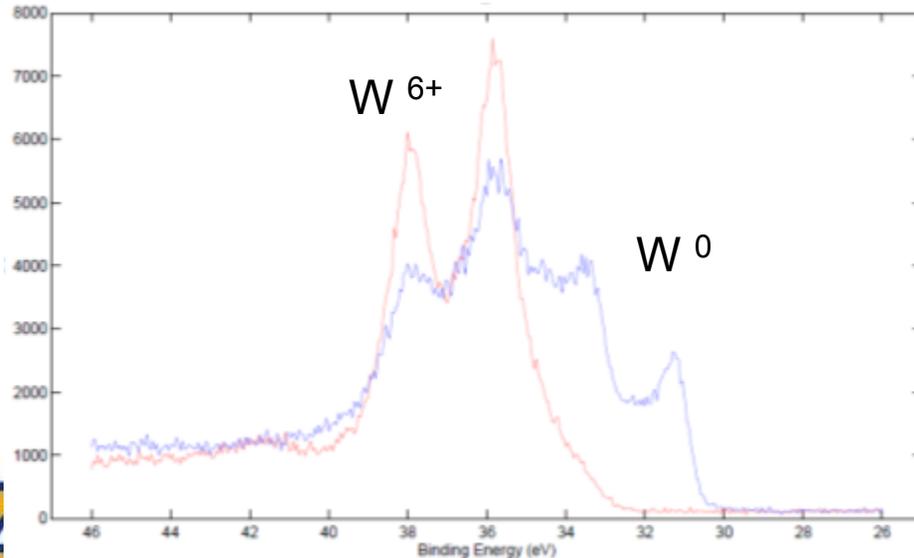


# Evaluation Sensing Materials for SO<sub>2</sub>

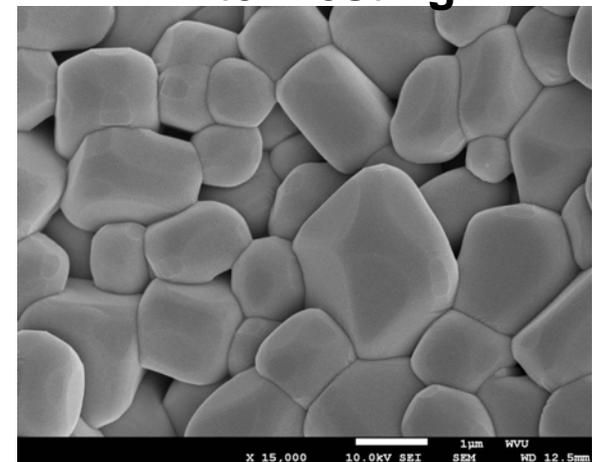
Why WO<sub>3</sub> is not capable of high temperature operation ?



- 5-100 nm nano-rods
- W<sup>+6</sup> are 35.67 and 37.85 and W<sup>+5</sup> 34.46 and 36.84 eV, color is light blue.
- 14.02% W<sup>+5</sup> and 85.98% W<sup>+6</sup> no other chemical state was detected.



After Testing

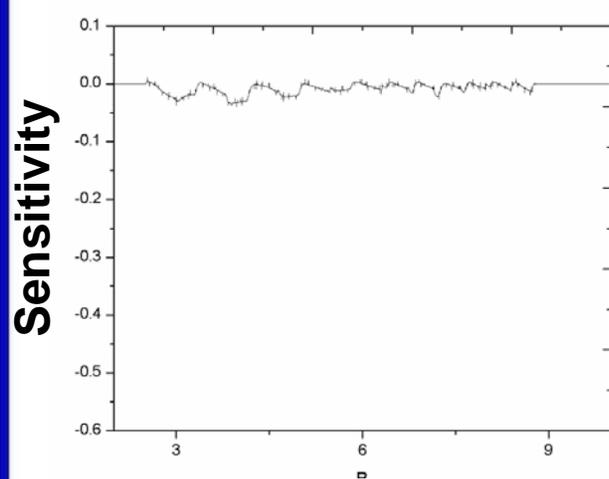


•Both macro and nano WO<sub>3</sub> showed similar reduction to metallic state (W<sup>0</sup>).

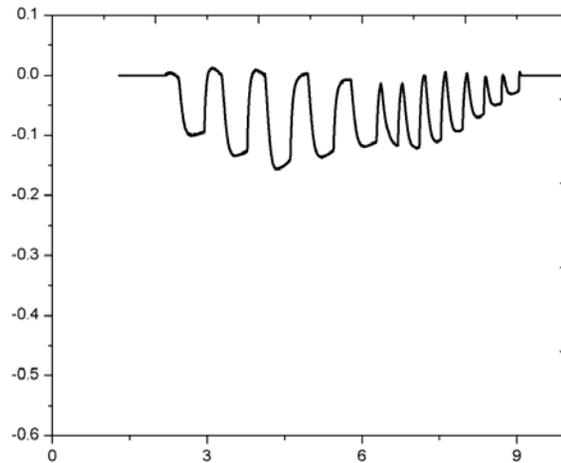
- Red : Air cooled
- Blue : N<sub>2</sub> cooled



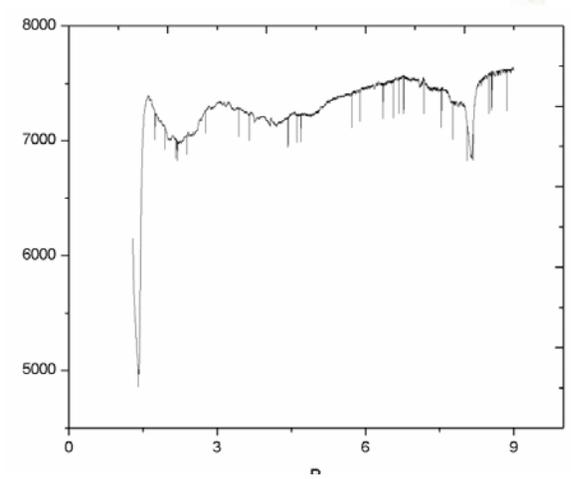
# Evaluation Sensing Materials for SO<sub>2</sub>



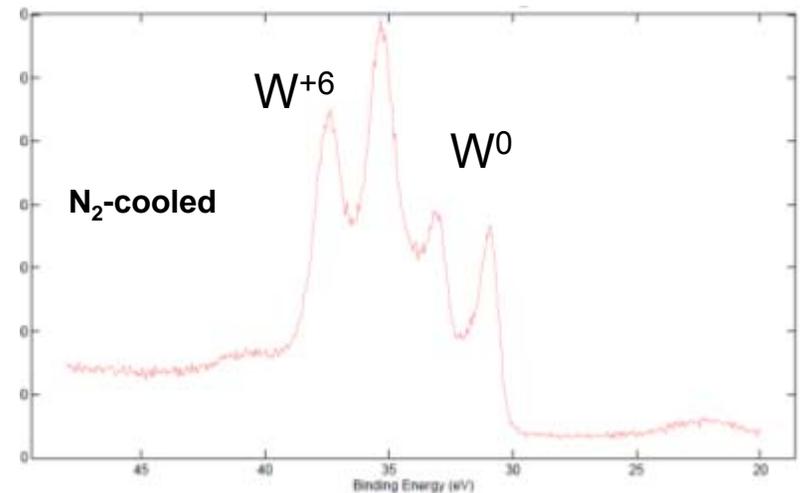
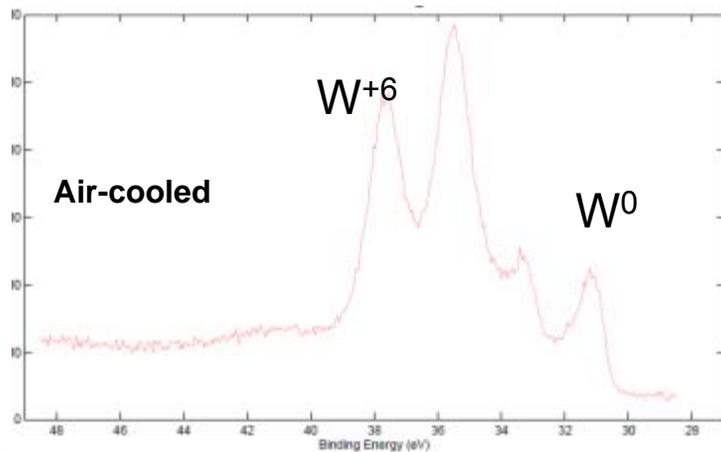
600°C 1%O<sub>2</sub> tested for SO<sub>2</sub>



800°C 1%O<sub>2</sub> tested for SO<sub>2</sub>

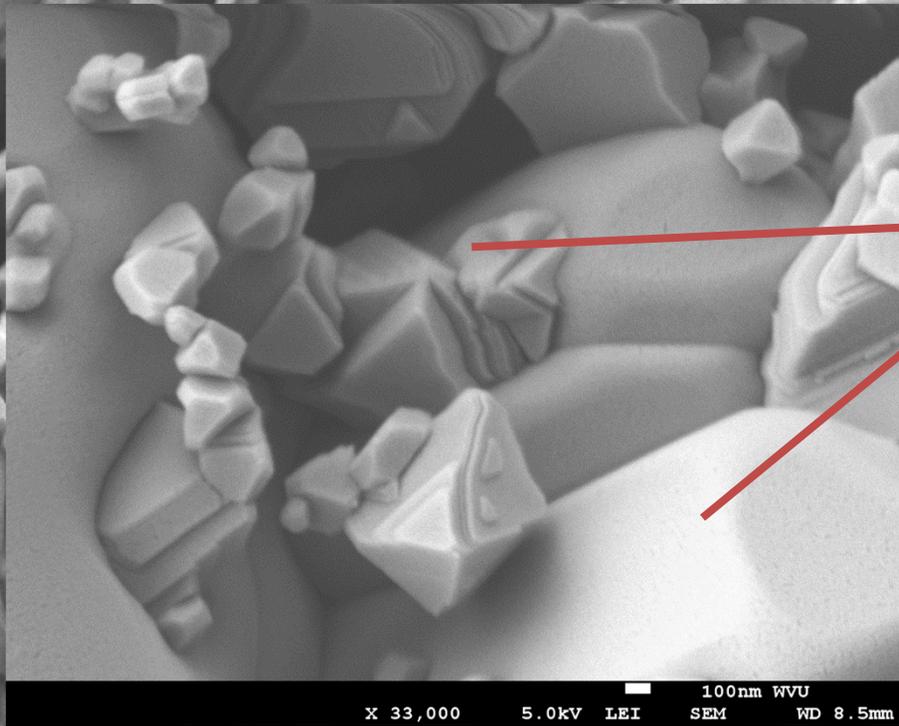


1000°C 1%O<sub>2</sub> tested for SO<sub>2</sub>



***NiWO<sub>4</sub>, similar reduction occurs at 1000°C***

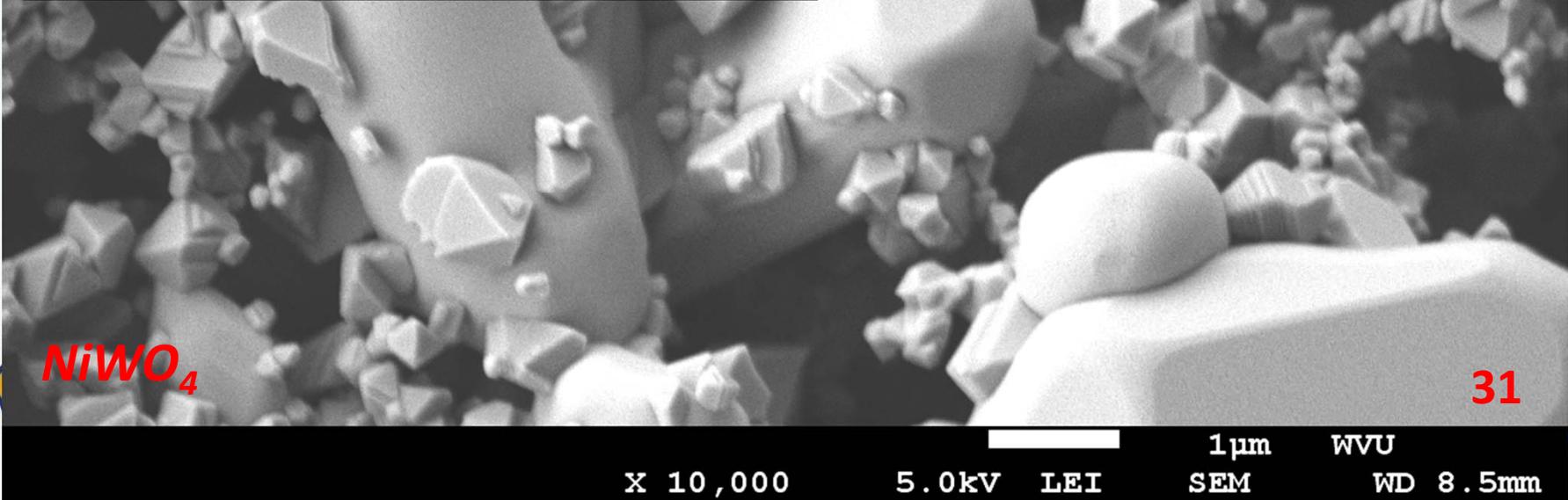
# Evaluation Sensing Materials for SO<sub>2</sub>



**Reduction (XPS, EDS confirmed not included) and accumulation of metallic Ni on Ni deficient WO<sub>3</sub> grains**

**NiWO<sub>4</sub>**

**31**



X 10,000

5.0kV

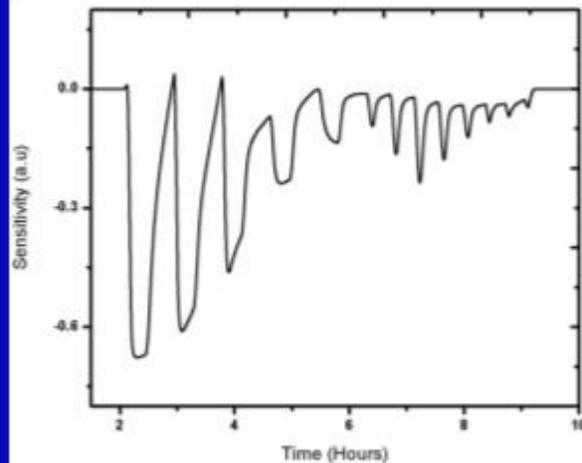
LEI

SEM

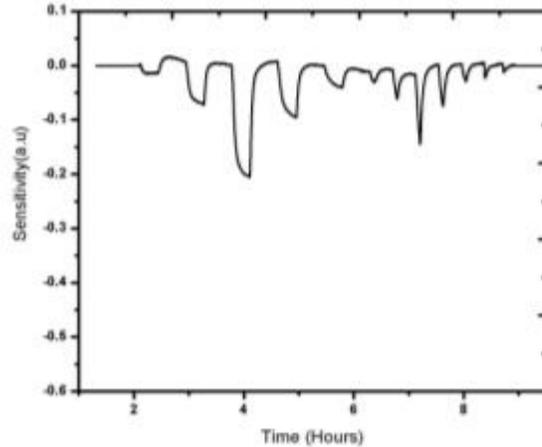
1µm WVU

WD 8.5mm

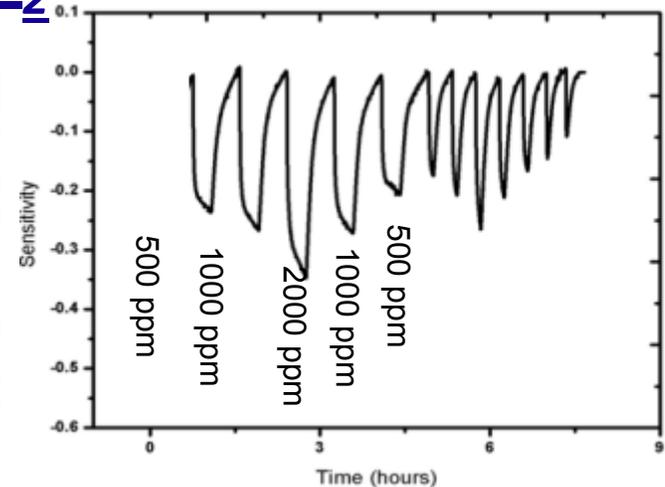
# Evaluation Sensing Materials for $SO_2$



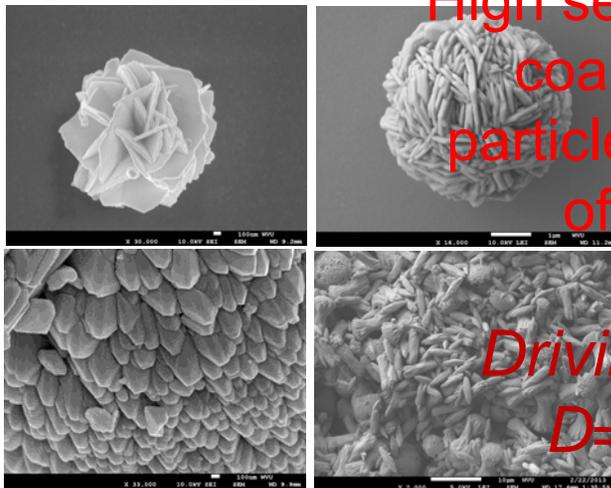
600°C 1%O<sub>2</sub> tested for SO<sub>2</sub>,



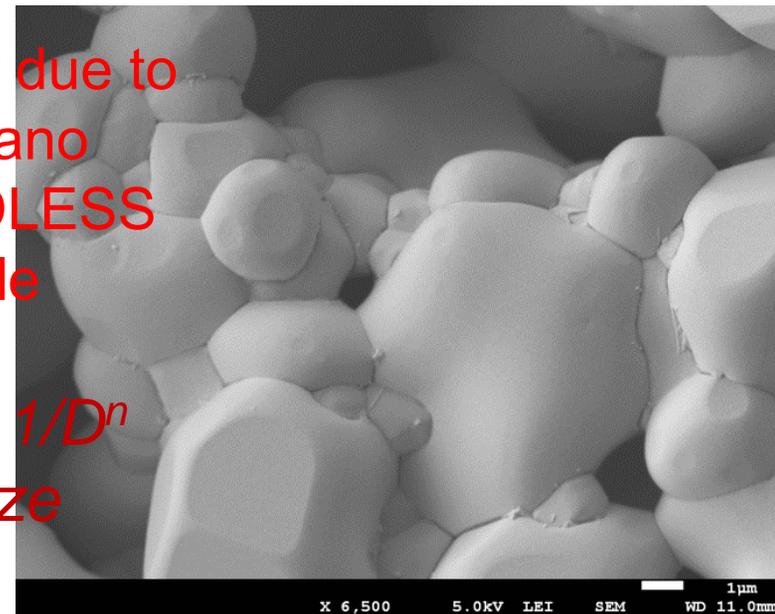
800°C 1%O<sub>2</sub> tested for SO<sub>2</sub>,



1000°C 1%O<sub>2</sub> tested for SO<sub>2</sub>,



High sensitivity lost due to coarsening of nano particles REGARDLESS of nano particle morphology  
 Driving Force  $\approx 1/D^n$   
 $D = \text{particle size}$   
 $n = 1, 2,$



SrMoO<sub>4</sub> powders with different morphologies, confirmed by XRD not included.

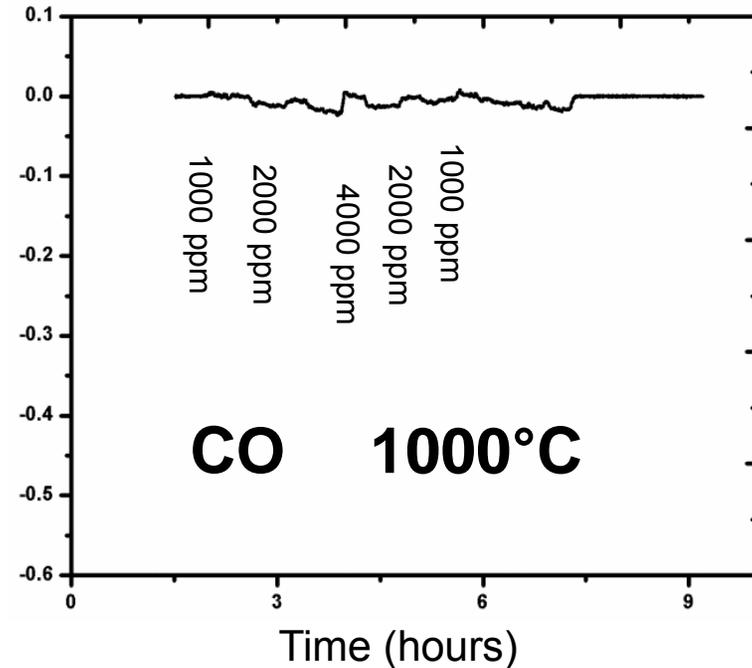
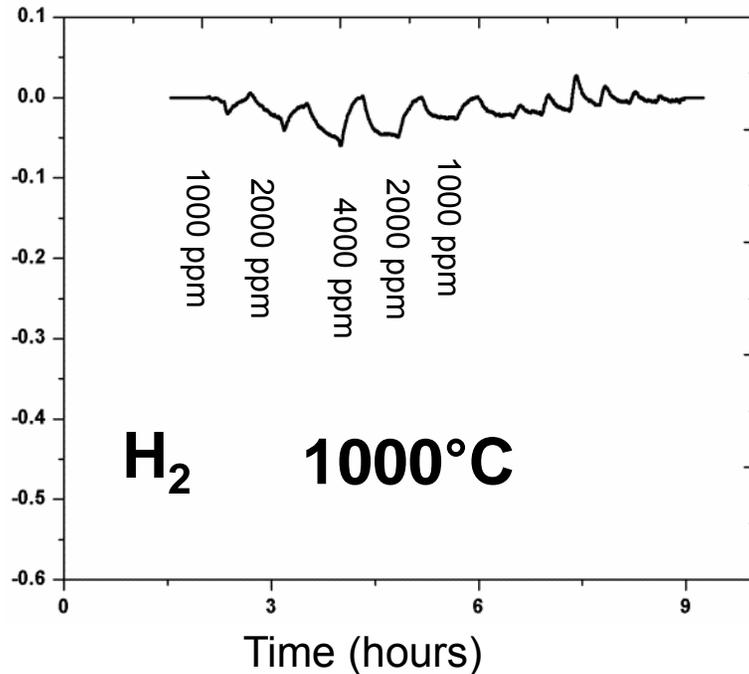
Nano-SrMoO<sub>4</sub>



## Evaluation Sensing Materials for SO<sub>2</sub>-Cross-Sensitivity Tests

H<sub>2</sub> concentration (4000 ppm) level is always two times than that of SO<sub>2</sub> (2000 ppm)

CO concentration (4000 ppm) level is two times than that of SO<sub>2</sub> (2000 ppm)



•**CROSS-SENSITIVITY ! TESTS SHOWED APPLICABILITY of nano-SrMoO<sub>4</sub> further !**



## Summary: Evaluation Sensing Materials for SO<sub>2</sub>

**SrMoO<sub>4</sub> and SrWO<sub>4</sub> showed**

- **Highest sensitivities at high temperature**
- **Lowest cross-sensitivities against CO and H<sub>2</sub>**
- **Long term stability (100 h)**



## Evaluation Sensing Materials for H<sub>2</sub>S

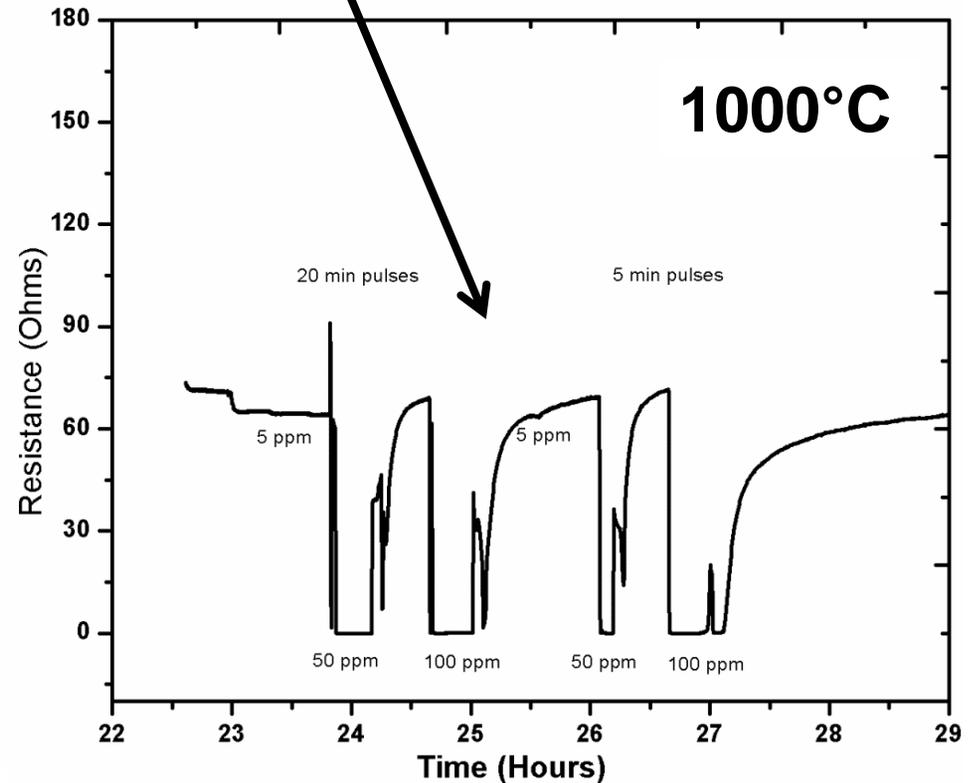
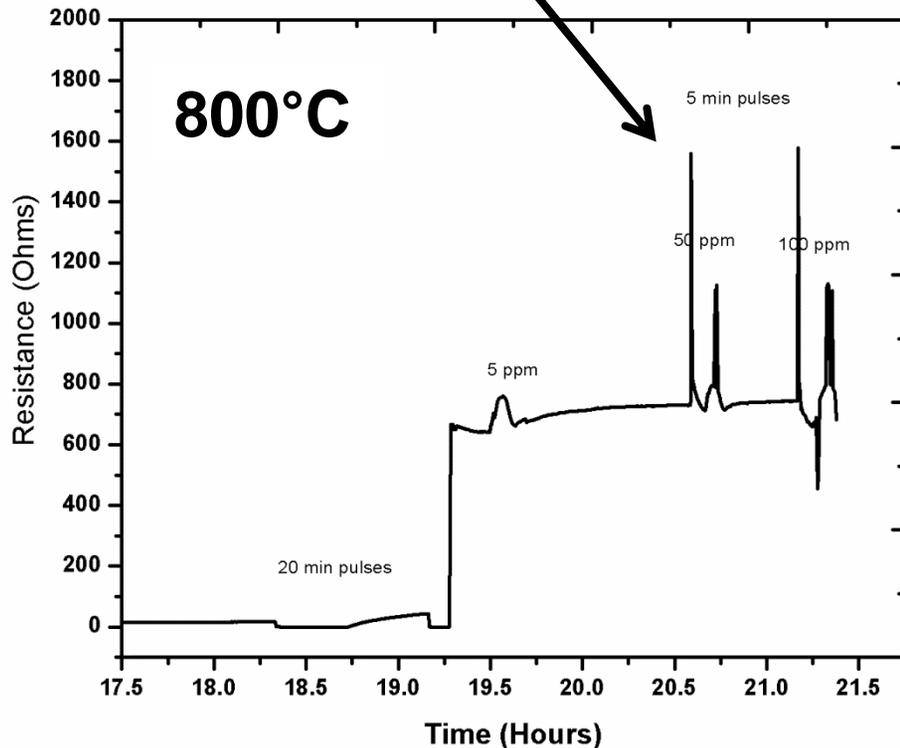
### SrMoO<sub>4</sub>, SrWO<sub>4</sub>, NiWO<sub>4</sub>

- The tests were conducted with 5, 50 and 100 ppm H<sub>2</sub>S balanced with H<sub>2</sub> and 1% O<sub>2</sub> Background.



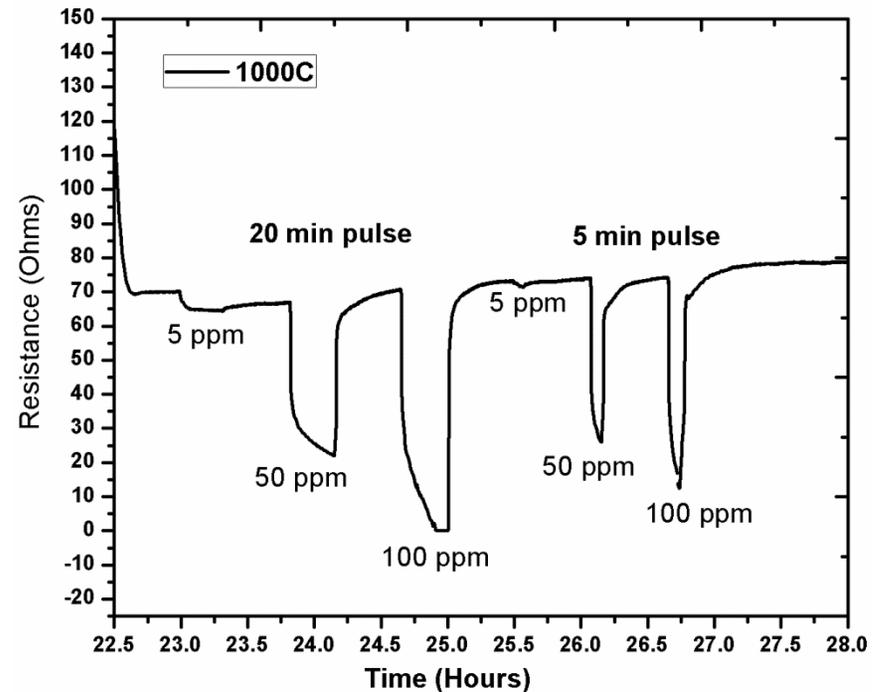
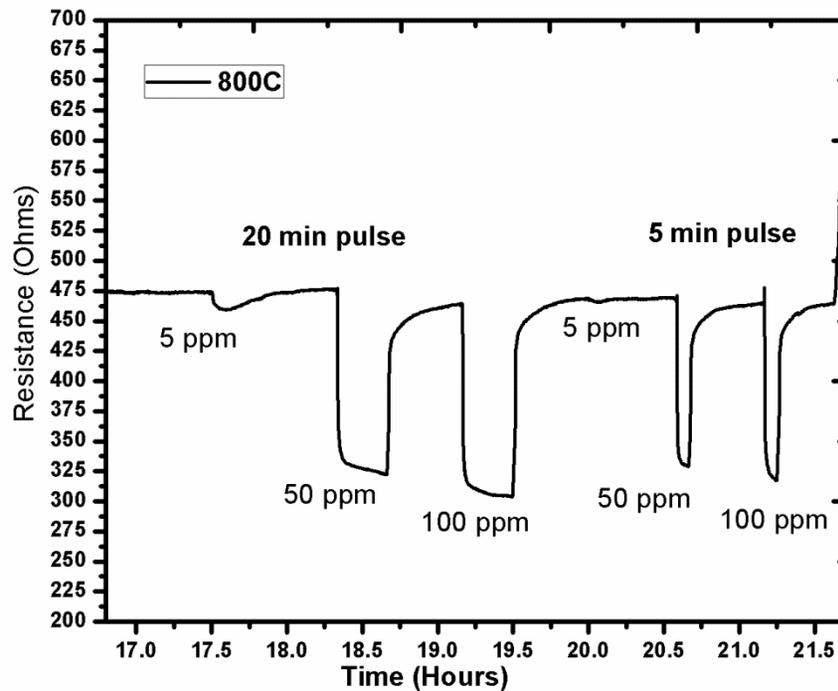
# Evaluation Sensing Materials for H<sub>2</sub>S

•800°C p-type, however 1000°C as expected n-type response.



- Not able to distinguish, 5, 50, and 100 ppm H<sub>2</sub>S at 800 and 1000°C
- Long term stability (48 h testing) test showed similar reduction behavior.

# Evaluation Sensing Materials for H<sub>2</sub>S

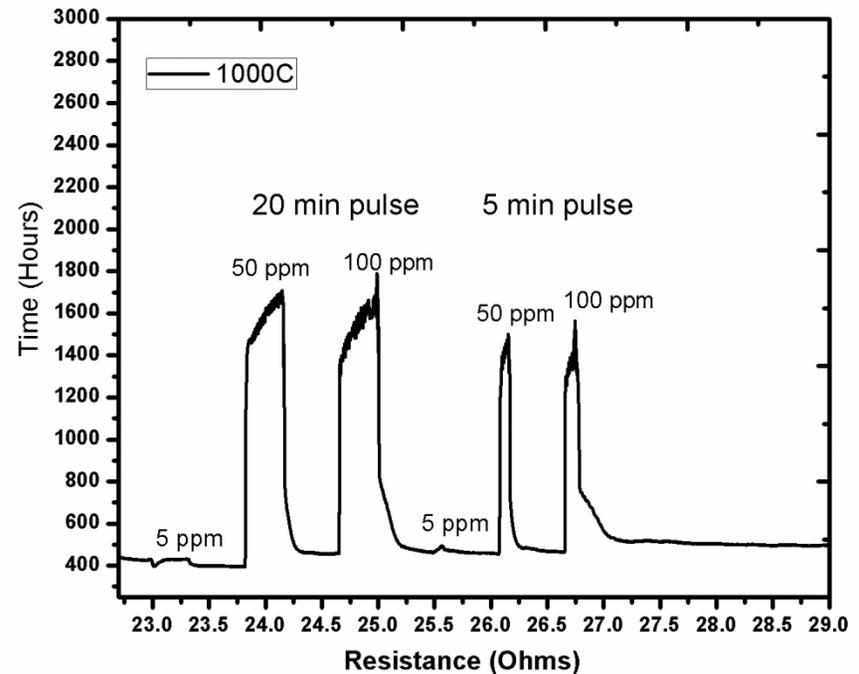
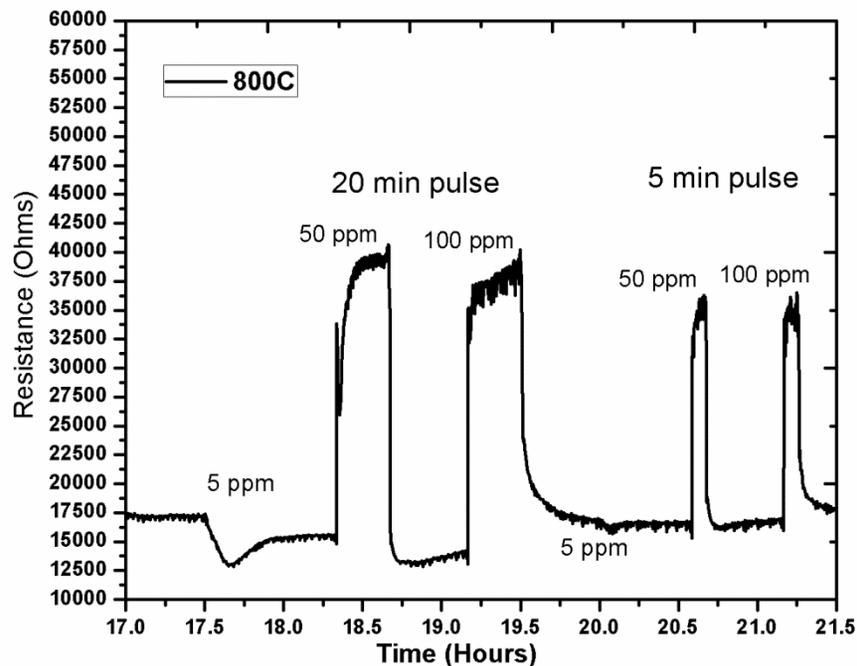


- Sensitive towards 5, 50, and 100 ppm H<sub>2</sub>S at 800 and 1000°C
- N-type behavior
- Long term stability (48 h testing) test showed similar sensing behavior.



Nano- SrMoO<sub>4</sub>

# Evaluation Sensing Materials for H<sub>2</sub>S

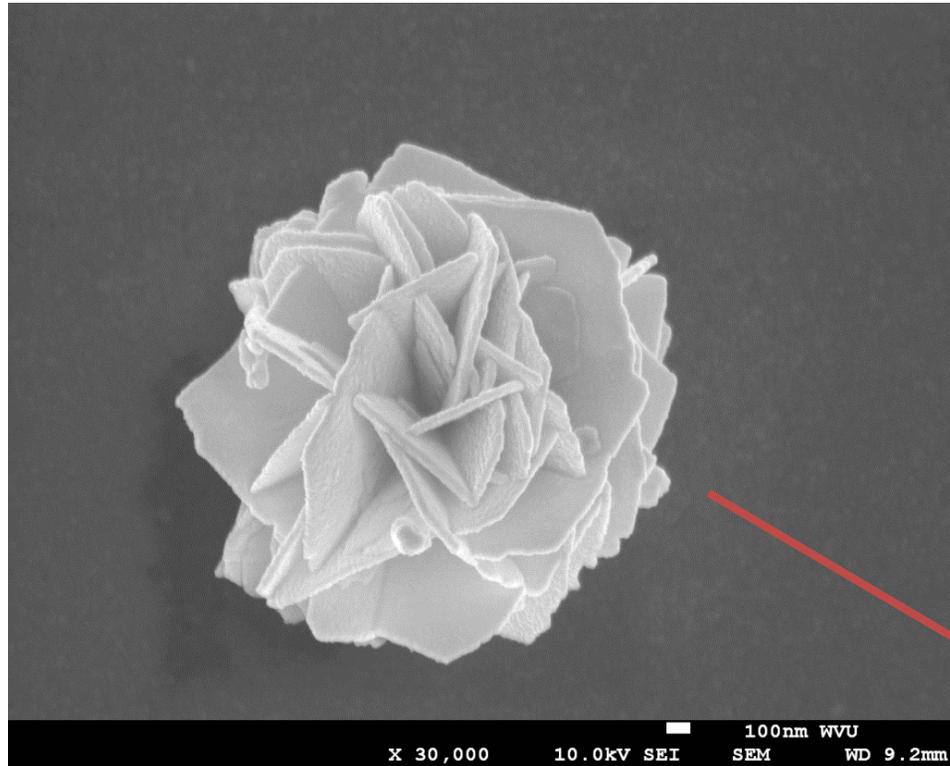


- Sensitive towards 5, 50, and 100 ppm H<sub>2</sub>S at 800 and 1000°C
- P-type behavior
- Long term stability (48 h testing)



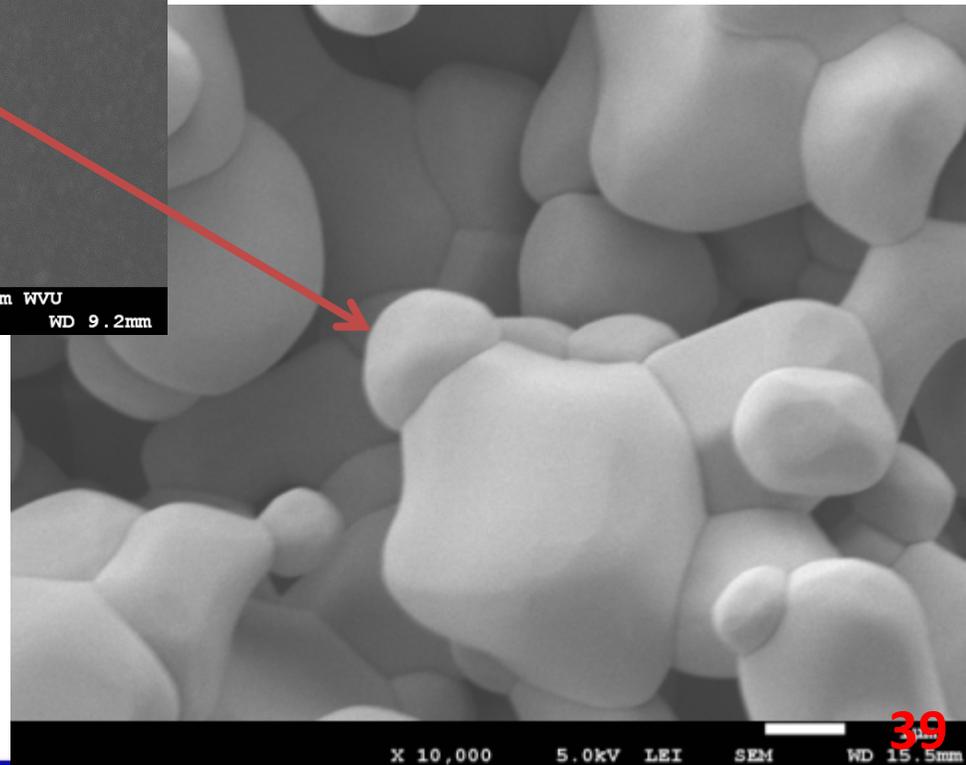
SrWO<sub>4</sub>

# NANOMATERIAL STABILIZATION EFFORTS



Regardless of morphology (5 different morphology were tried) this is what happens at elevated temperature !!!

**Nano- SrMoO<sub>4</sub>**





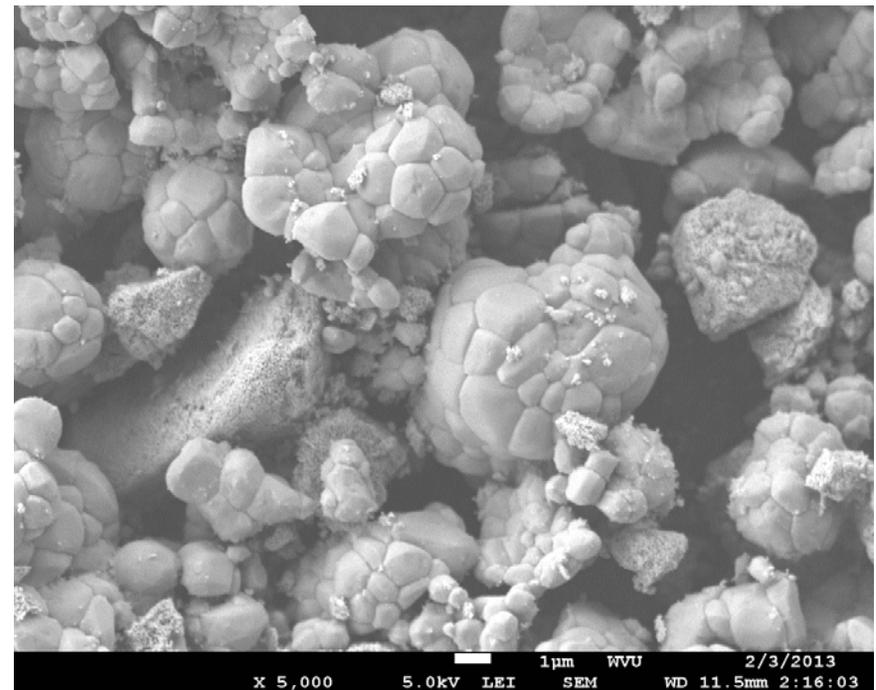
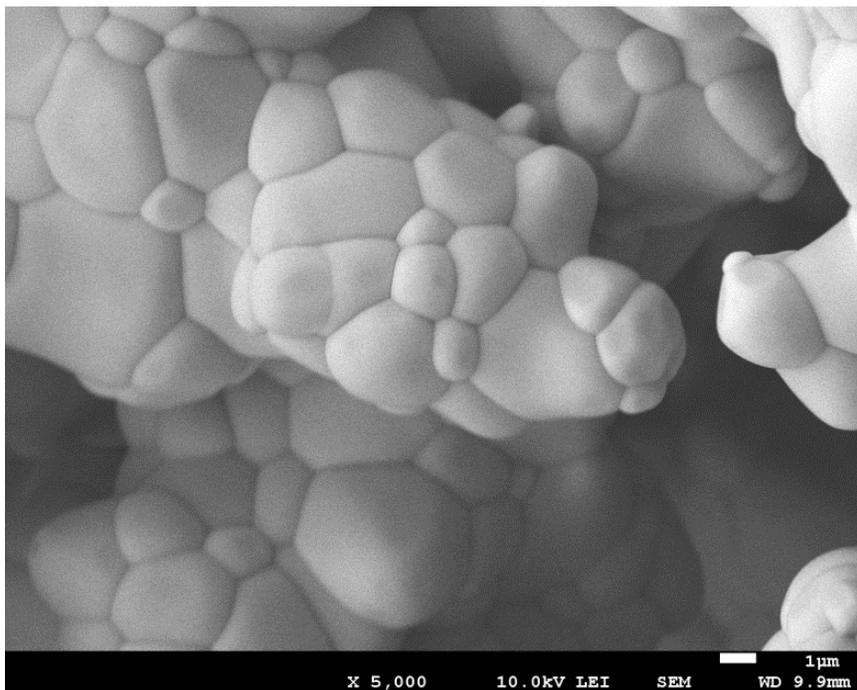
**Possible Solutions to stop the coarsening of nano-SrMoO<sub>4</sub>**

- 1. Grain pinning**
- 2. Templated growth of SrMoO<sub>4</sub>, over a core refractory-oxide structure**



# NANOMATERIAL STABILIZATION EFFORTS

## 1. Grain pinning

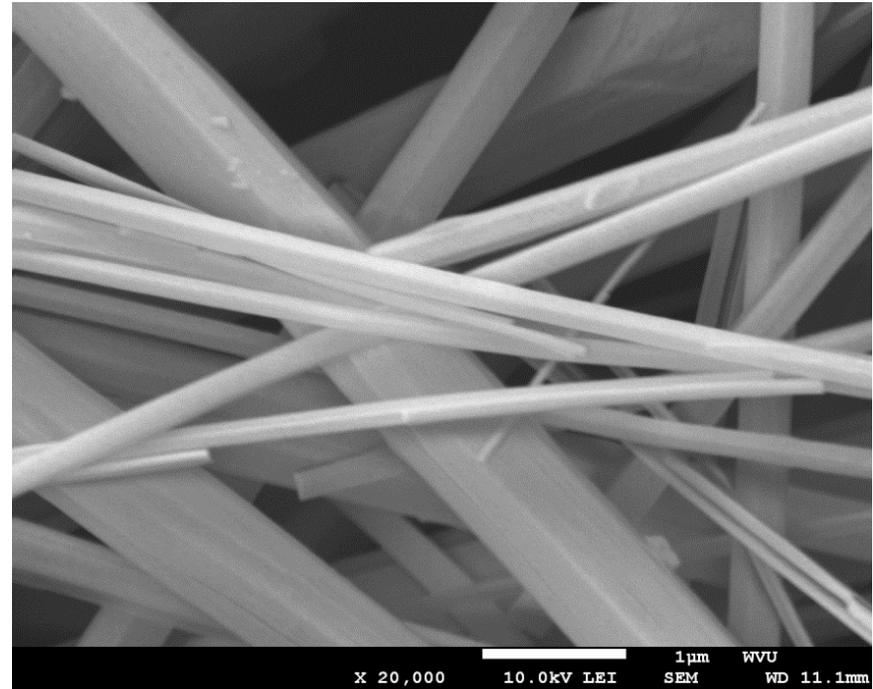
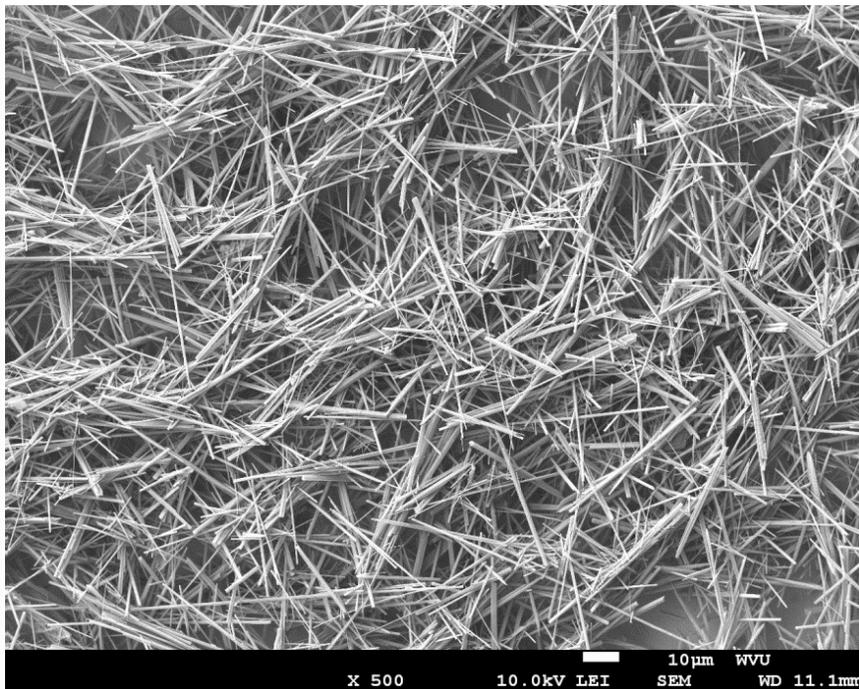


• Limited success !!!



# NANOMATERIAL STABILIZATION EFFORTS

## 2. Templated growth of $\text{SrMoO}_4$ , over a core refractory-oxide structure.

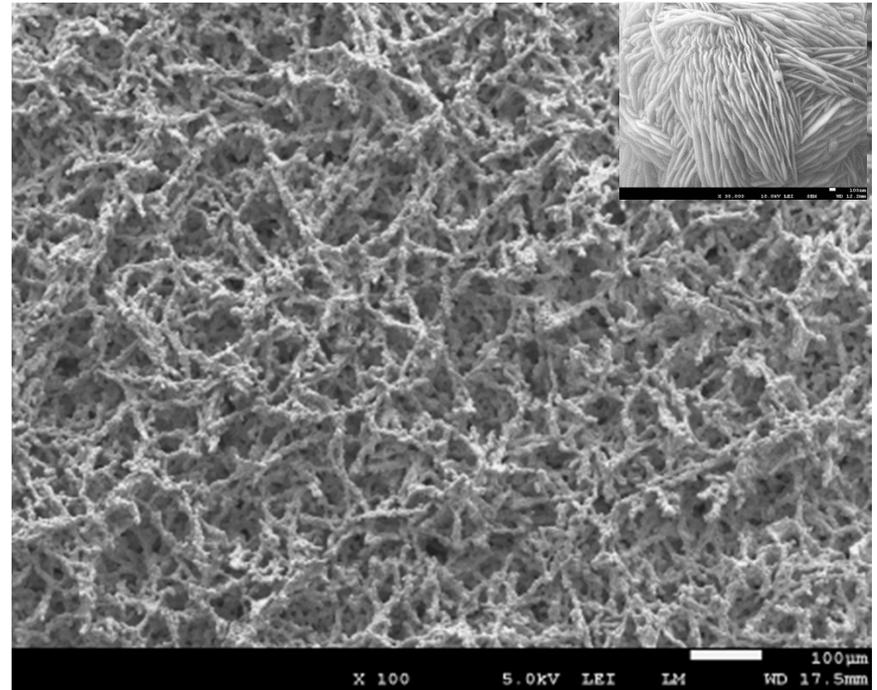
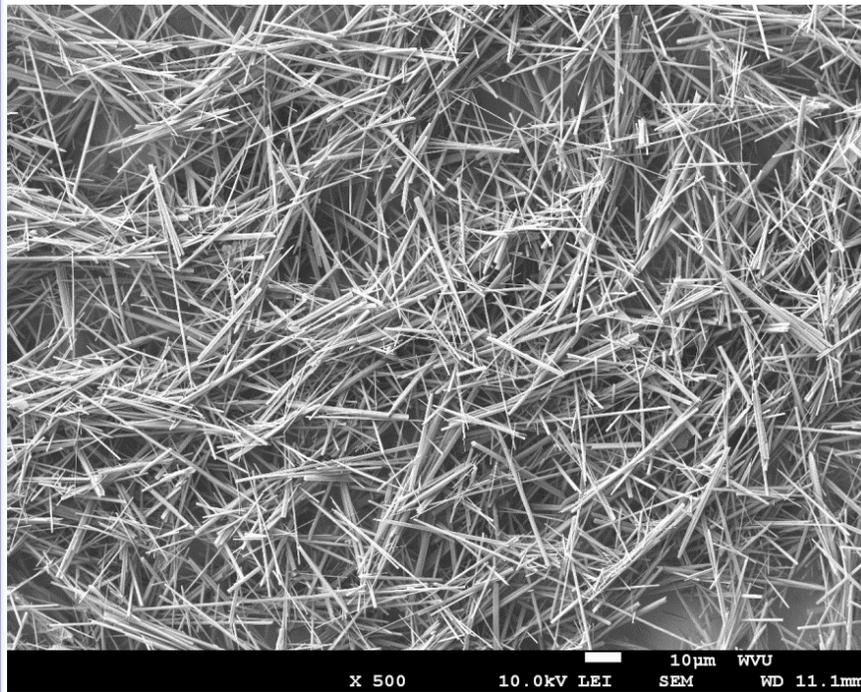


- For this purpose, MgO nanorods were synthesized.



# NANOMATERIAL STABILIZATION EFFORTS

**2. Lost-Template Growth**, over a core refractory structure with nano-features.  
Core structure totally lost, confirmed by XPS, EDS and XRD not included.



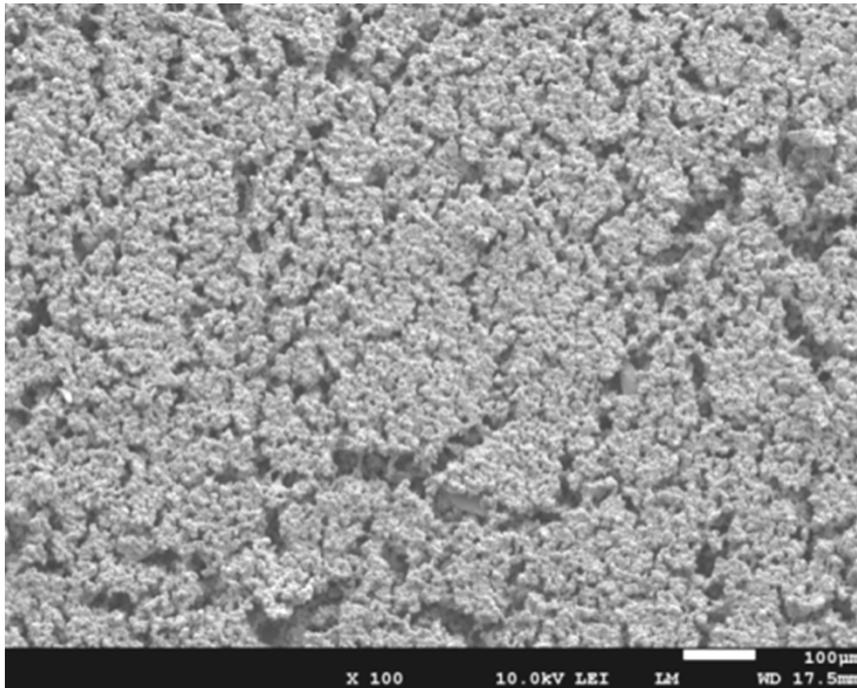
And tried grow  $\text{SrMoO}_4$  over  $\text{MgO}$ , worked...



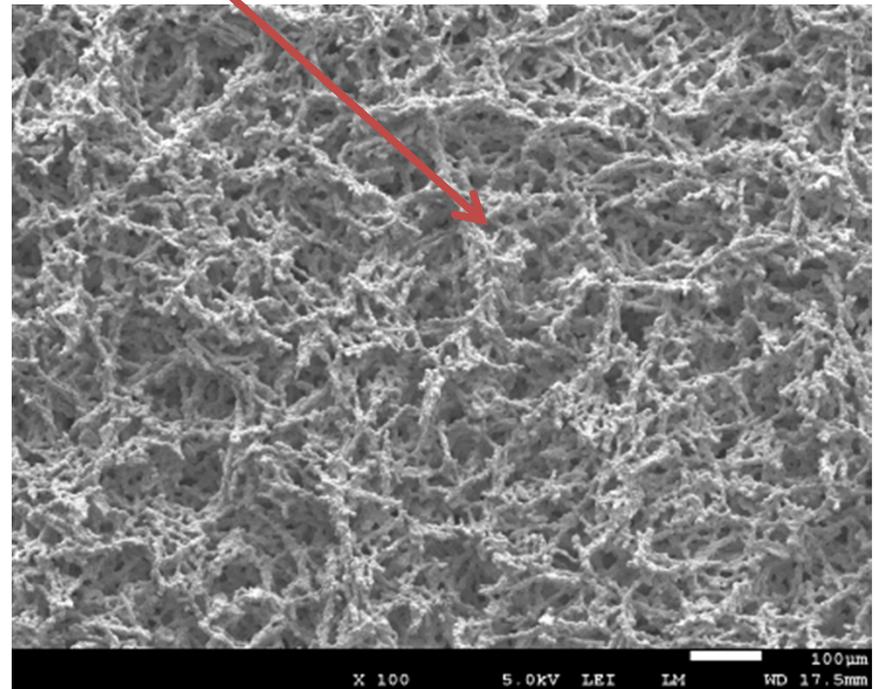
# NANOMATERIAL STABILIZATION EFFORTS

## COMPARISON

•Higher surface area and very porous network for efficient gas penetration survived...Temporary testing facility established and this material about to be tested.



•SrMoO<sub>4</sub> nano-flowers after 5 h 1000°C in air.

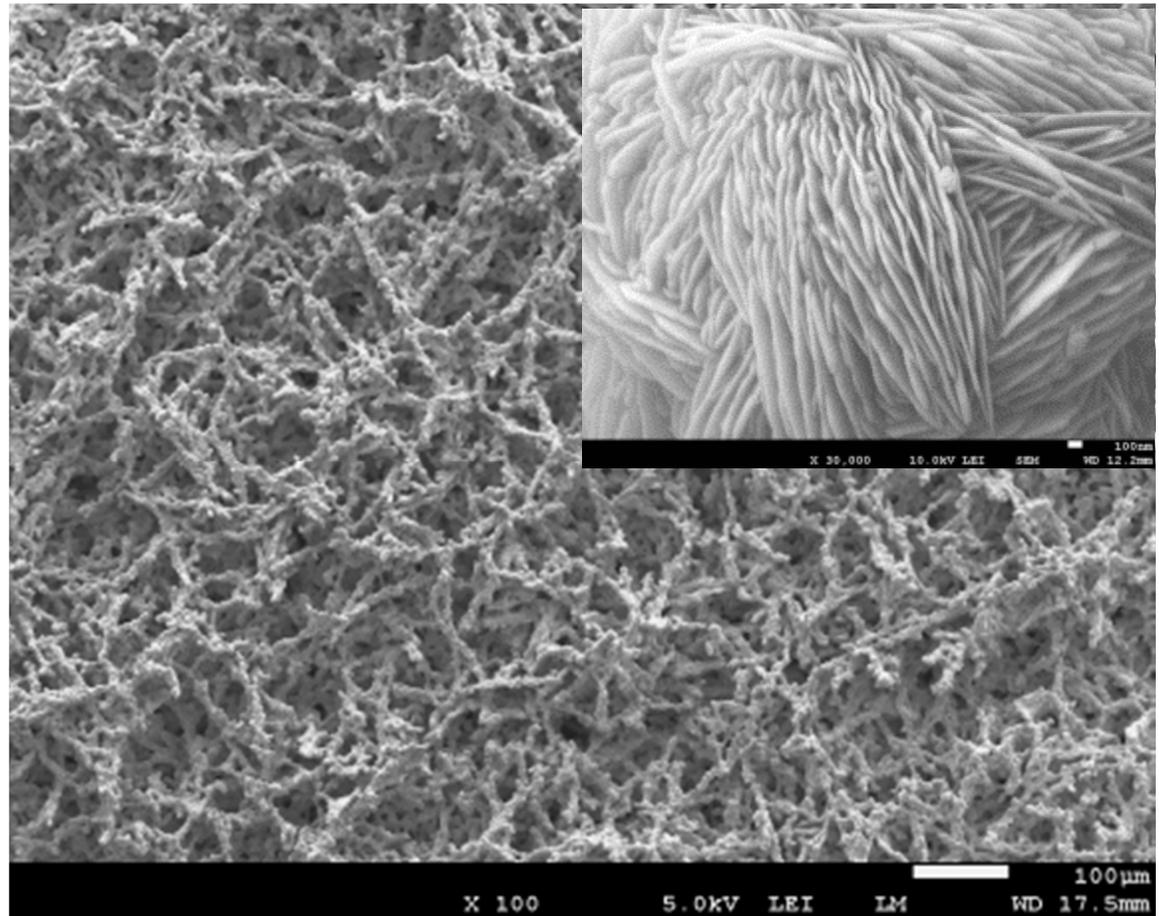


•SrMoO<sub>4</sub> nano-flowers over MgO after 5 h 1000°C in air.



## SUMMARY: Nano-Derived Sensing Materials And Testing

- $\text{SrMoO}_4$  and  $\text{SrWO}_4$  showed superior sensing capabilities at high temperature.
- High-temperature coarsening resistant  $\text{SrMoO}_4$  was synthesized by lost-template method showed increased sensitivity.
- Long term stability tests showed reliability of the  $\text{SrMoO}_4$  and  $\text{SrWO}_4$

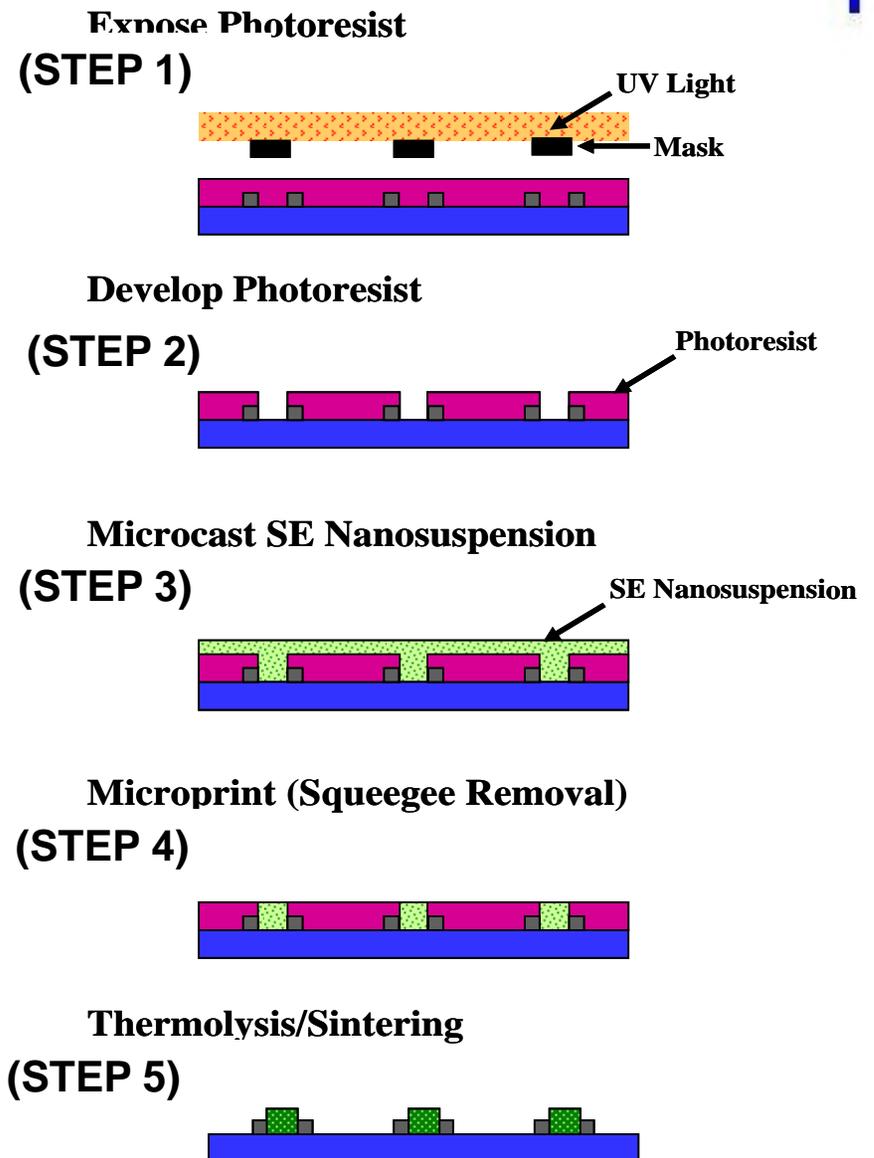


***Micro-Sensor and -Array Fabrication  
and Testing***



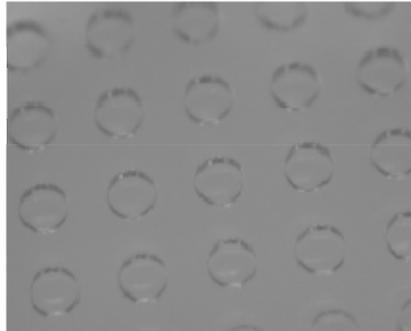
# Micro-sensor Array Fabrication

- 1) Negative lithography used for micro-molds
  - SU8-25 (Microchem)
    - From 20-90  $\mu\text{m}$  depth depending on spin rate
  - OAI UV Flood Exposure System
  - SU8 developer
- 2) Sensing material is casted into mold.
- 3) Mold is burned off and material is sintered or bonded to substrate.



# Micro-sensor Array Fabrication

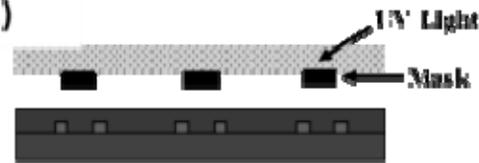
SU8 Micro-mold



250  $\mu\text{m}$

## Expose Photoresist

(STEP 1)



## Develop Photoresist

(STEP 2)



## Microcast SE Nanosuspension

(STEP 3)



## Microprint (Squeegee Removal)

(STEP 4)

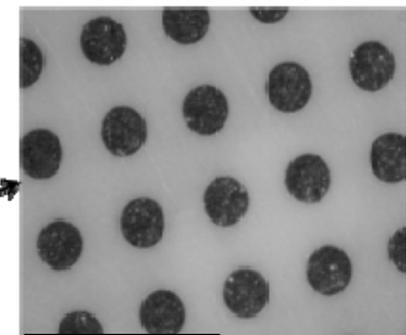


## Thermolysis/Sintering

(STEP 5)

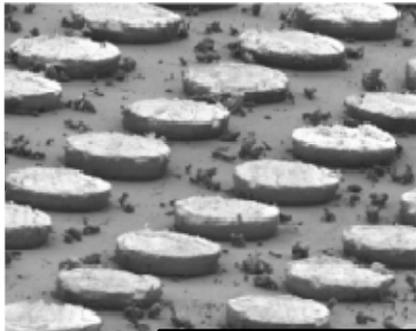


Micro-casted into Micro-molds



250  $\mu\text{m}$

Thermally Processed Features



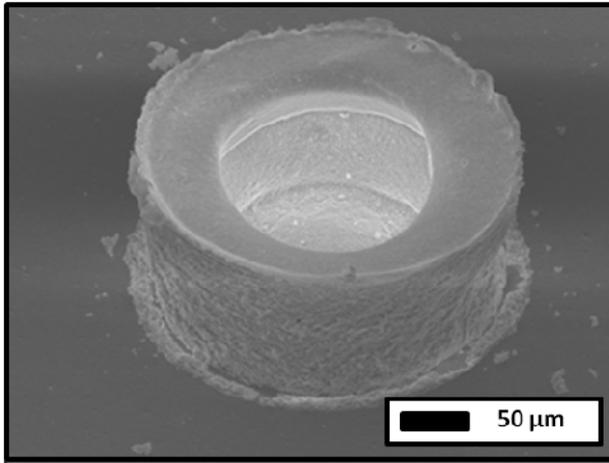
250  $\mu\text{m}$



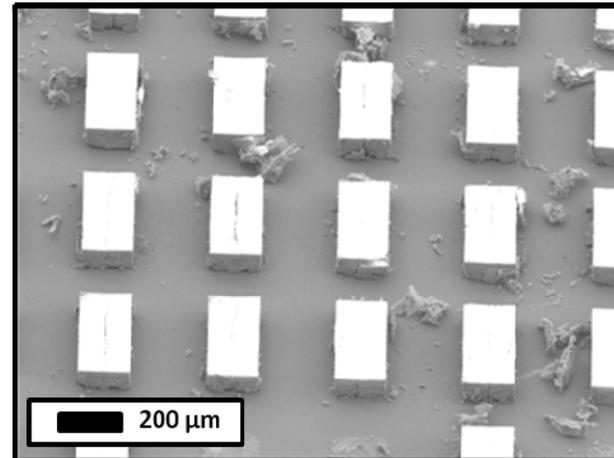
# Micro-Casting - SEM

•Casted single layer on YSZ substrate

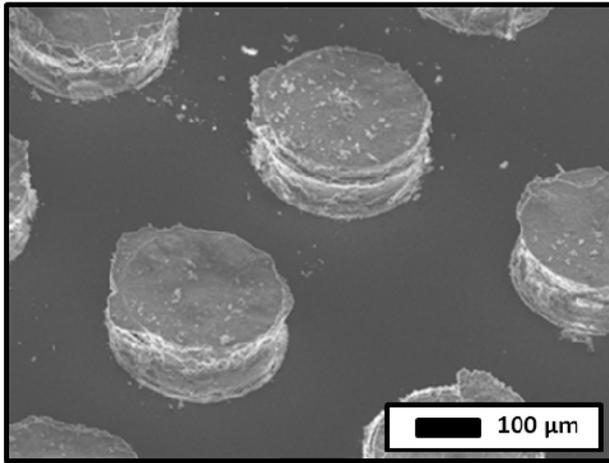
•Casted double layer on YSZ substrate



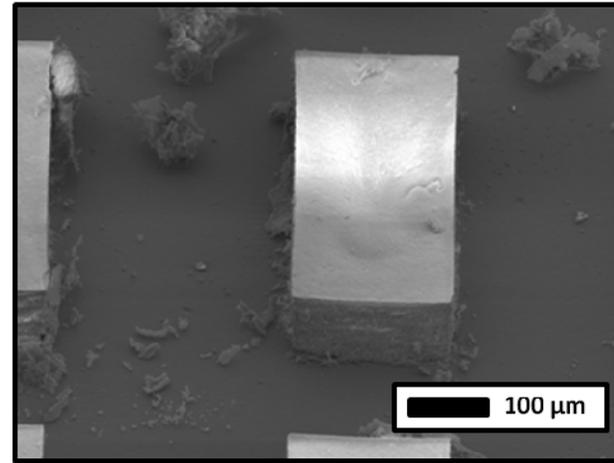
(a)



(b)



(c)

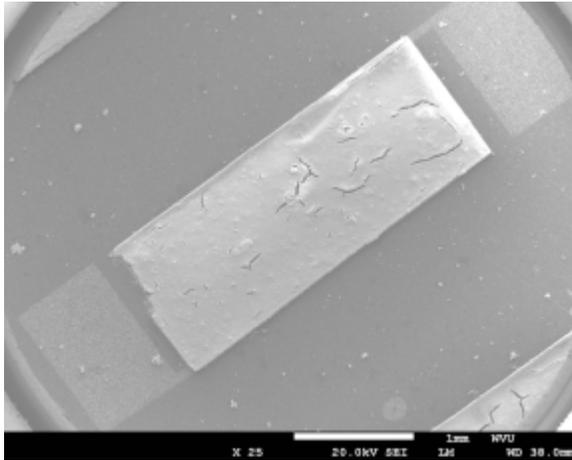


(d)

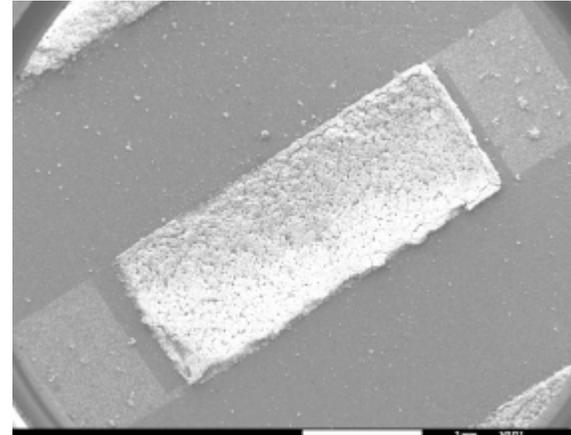


# Micro-casting of Sensor Arrays

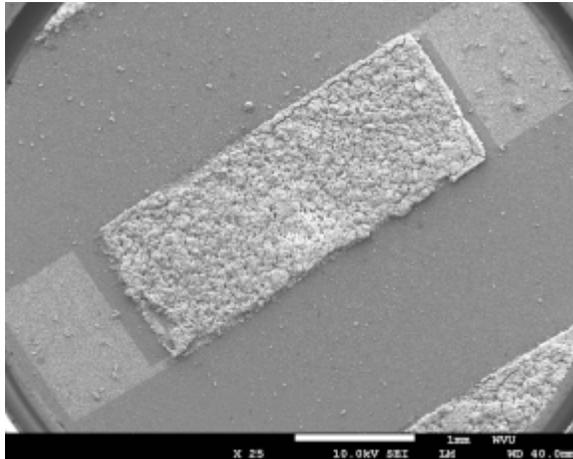
Nano-SnO<sub>2</sub>



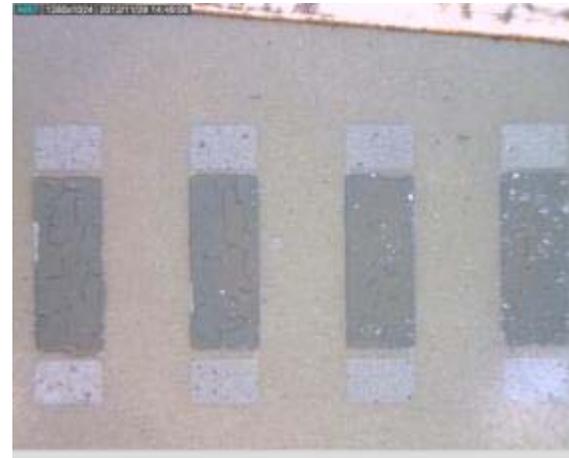
Nano-10% SnO<sub>2</sub>/90% Gd<sub>1.8</sub>Y<sub>0.2</sub>Zr<sub>2</sub>O<sub>7</sub>



Nano-Gd<sub>2</sub>Zr<sub>2</sub>O<sub>7</sub>



Nano-SnO<sub>2</sub> and Gd<sub>1.8</sub>Y<sub>0.2</sub>Zr<sub>2</sub>O<sub>7</sub> Arrays

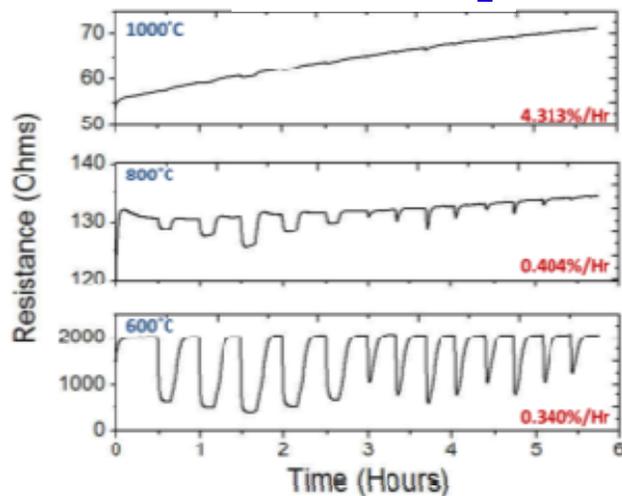


Micro-sensor and arrays fabricated with nano-SnO<sub>2</sub> and nano-SnO<sub>2</sub>/zirconate materials.

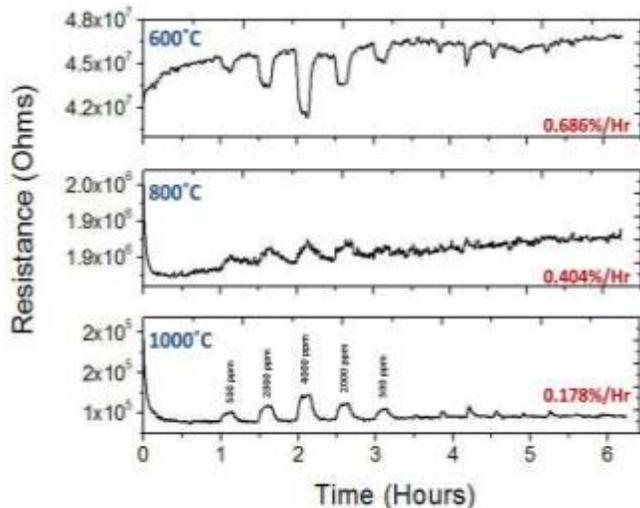


## Initial Micro-sensor Testing (with Nanomaterials)

### Nano-SnO<sub>2</sub>



### Nano-10% SnO<sub>2</sub>/90% GZO



(b)

- Micro-IDEs were fabricated by sputtering process.
- 29 fingers were spaced 50  $\mu\text{m}$  apart with a sensing area of 1.2 mm x 3 mm.

### SnO<sub>2</sub> sensor

- Sensitivity of 0.812 and 0.010 at 600 and 800°C to 4000 ppm of H<sub>2</sub>

### 10% SnO<sub>2</sub>/90% GZO sensor

- Sensitivity of 0.097 and 0.047 sensitivity at 600 and 1000°C, respectively, to 4000 ppm of H<sub>2</sub>

### Compared to Macro-Sensors

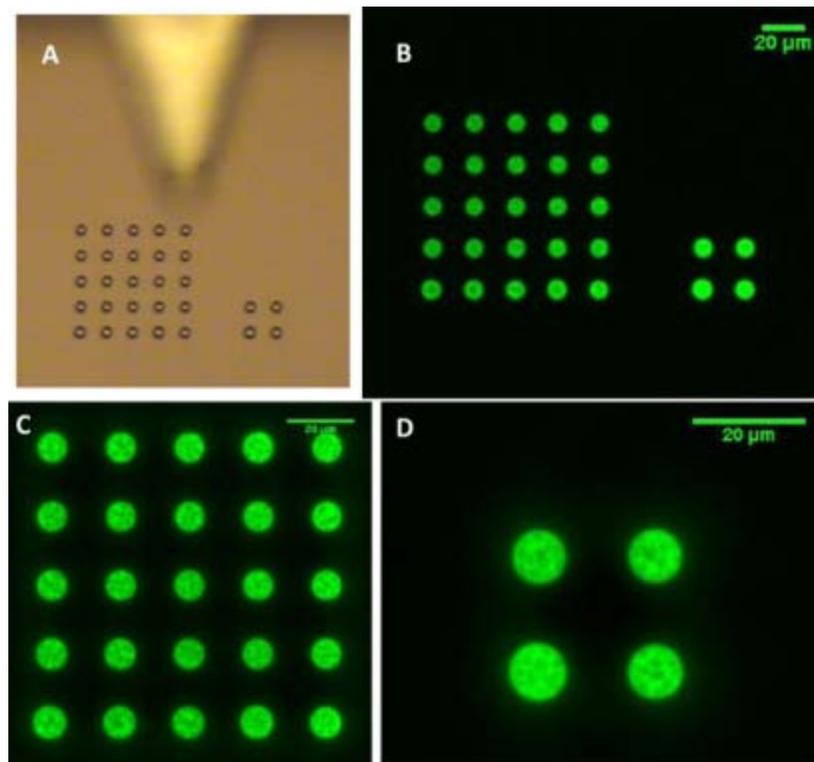
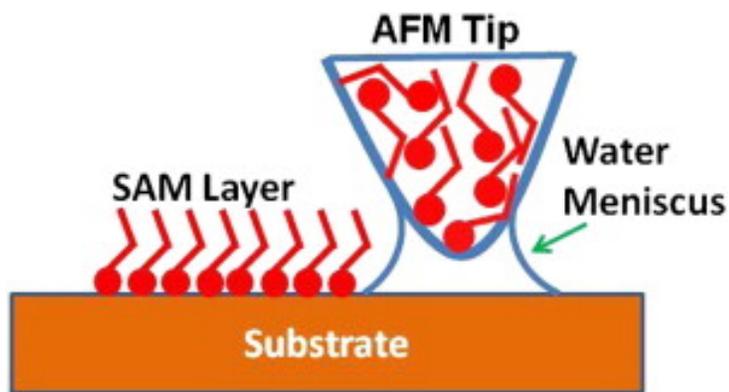
- ~63% increase in response rate
- ~200% increase in sensitivity

N<sub>2</sub> with ppm H<sub>2</sub> (10% oxygen atmosphere)

# Micro-Patterning Techniques

## Dip Pen Nanolithography (DPN)

- Direct drawing delivers multiple materials onto a single substrate.
- Typically used to deposit organic material (DNA, cells, peptides, polymers).

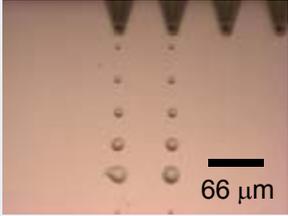
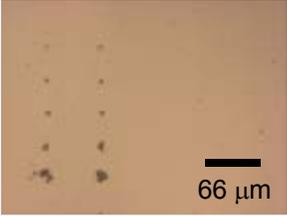
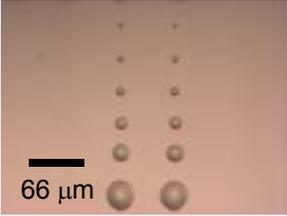
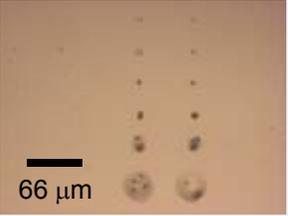
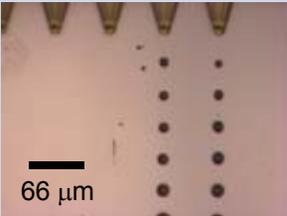
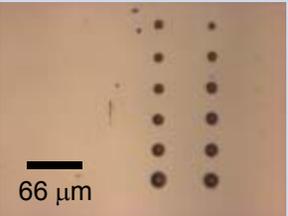


Thompson et al., Biosensors and Bioelectronics, 26 (2011).

Agarwal et al., Thin Solid Films, 519(2010).



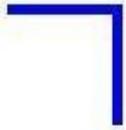
# DPN of Nano-Inks on Untreated Substrate

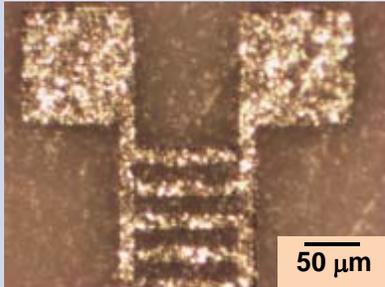
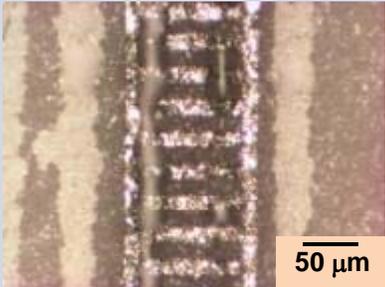
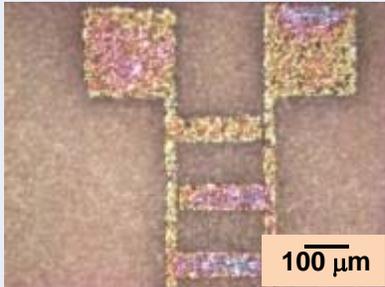
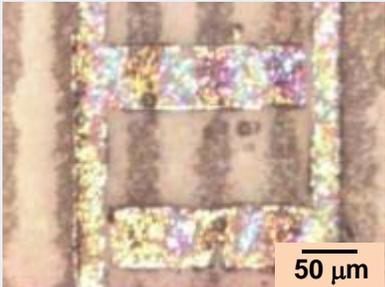
	Ink #1		Ink #2	
	Wet	Dry	Wet	Dry
Glass				
Alumina				

- Ink shows  $\theta \approx 35^\circ$  on both substrates.
- Uniform size and shape dots (5-10  $\mu\text{m}$ ) possible on alumina substrate.
- Ink #2 dots on alumina substrate retain shape through drying.
- Direct-writing of continuous line not possible on neither substrates (contact angle too high,  $>25^\circ$  for line drawing).



# DPN of Nano-Inks on Electroded Ceramic Substrates

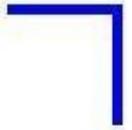


	Substrate	Pattern with Ink #2
No coating		
CTAB coating		

- Patterning on ceramic (polycrystalline ) substrate with metallic electrodes.
- Difficult due to difference in wetting characteristics of each grain and metal vs. ceramic.
- Ink pattern on a substrate **without a coating** shows the ink **stumbling over the metallic/ceramic interchanges.**
- CTAB coating provides a single chemistry surface over the IDEs on multigrain ceramic substrate.
- CTAB coating enables patterning of inks.



# Work Summary



## ***1. High-temperature interdigitized electrodes (IDEs).***

- ***High temperature IDEs (stable to 1000 °C) were developed and method for micro-patterning.***

## ***2. Sensing Materials for Sulphur Compounds.***

- Ternary tungstates and molybdates were synthesized at the micron- and nano-scale, and tested for H<sub>2</sub>, SO<sub>2</sub> and H<sub>2</sub>S.
- High sensitivities were measured >800°C, but the as-synthesized nanomaterial morphology was not stable.

## ***3. High-temperature Stabilization of Ternary Mo/W Nanomaterials***

- Nano-SrMoO<sub>3</sub> (which showed high sensitivity to SO<sub>2</sub>) was grown over nano-fiber MgO to form a high-temperature stable nano-morphology.

## ***4. Micro-sensors and Array Fabrication***

- Micro-molding process was developed to deposit forms down to ~10µm.
- Micro-sensors and basic arrays (with synthesized nanomaterials) were fabricated on stable IDEs.



## *Future Work*

- Alternative core structures for templated growth of nanomaterials.
- Fabrication and testing of the micro-sensor platform for SO<sub>2</sub>, H<sub>2</sub> and H<sub>2</sub>S.
- Longer term testing of the micro-sensors for >100 h.
- Further investigation of sensing mechanism by ECR (electrochemical relaxation) supported by XPS and FT-IR.



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